CPC COOPERATIVE PATENT CLASSIFICATION

G PHYSICS

(NOTES omitted)

INSTRUMENTS

G11 INFORMATION STORAGE

G11C STATIC STORES (semiconductor memory devices H10B)

NOTES

- 1. This subclass <u>covers</u> devices or arrangements for storage of digital or analogue information:
 - in which no relative movement takes place between an information storage element and a transducer;
 - · which incorporate a selecting-device for writing-in or reading-out the information into or from the store.
- 2. This subclass <u>does not cover</u> elements not adapted for storage and not provided with such means as referred to in Note (3) below, which elements are classified in the appropriate subclass, e.g. of <u>H01</u>, <u>H03K</u>.
- 3. In this subclass, the following terms are used with the meaning indicated:
 - "storage element" is an element which can hold at least one item of information and is provided with means for writing-in or reading-out this information;
 - "memory" is a device, including storage elements, which can hold information to be extracted when desired.

WARNINGS

5/12

1. The following IPC groups are not in the CPC scheme. The subject matter for these IPC groups is classified in the following CPC groups:

G11C 8/02	covered by	G11C 8/00, H03K 17/00
G11C 11/4193	covered by	G11C 11/00
G11C 11/4195	covered by	G11C 11/00
G11C 11/4197	covered by	G11C 11/00

2. In this subclass non-limiting references (in the sense of paragraph 39 of the Guide to the IPC) may still be displayed in the scheme.

5/00 5/005	Details of stores covered by group G11C 11/00 • {Circuit means for protection against loss of information of comiced ductor stores advises.}	5/14	 Power supply arrangements {, e.g. power down, chip selection or deselection, layout of wirings or power grids, or multiple supply levels}
5/02	information of semiconductor storage devices}Disposition of storage elements, e.g. in the form of a matrix array	5/141 5/142	 • {Battery and back-up supplies} • {Contactless power supplies, e.g. RF, induction,
5/025	 (Geometric lay-out considerations of storage- and peripheral-blocks in a semiconductor storage device (geometrical lay-out of the components in integrated circuits, geometrical lay-out of the components in integrated circuits <u>H10D 89/10</u>)} 	5/143	or IR } {Detection of memory cassette insertion or removal; Continuity checks of supply or ground lines; Detection of supply variations, interruptions or levels (G11C 5/148 takes
5/04	• • Supports for storage elements {, e.g. memory modules}; Mounting or fixing of storage elements	5/144	precedence); Switching between alternative supplies (G11C 5/141 takes precedence)}
5/05 5/06	on such supports Supporting of cores in matrix . Arrangements for interconnecting storage elements	5/144	 • {Detection of predetermined disconnection or reduction of power supply, e.g. power down or power standby}
	electrically, e.g. by wiring	5/145	• • {Applications of charge pumps; Boosted voltage circuits; Clamp circuits therefor (G11C 5/141
5/063	• • {Voltage and signal distribution in integrated semi-conductor memory access lines, e.g. word-		takes precedence)}
	line, bit-line, cross-over resistance, propagation delay}	5/146	• • {Substrate bias generators (G11C 5/141 takes precedence)}
5/066	• • {Means for reducing external access-lines for a semiconductor memory clip, e.g. by multiplexing at least address and data signals}	5/147	• • {Voltage reference generators, voltage or current regulators; Internally lowered supply levels; Compensation for voltage drops (G11C 5/141
5/08	for interconnecting magnetic elements, e.g. toroidal cores	5/148	takes precedence)}• {Details of power up or power down circuits,
5/10	for interconnecting capacitors		standby circuits or recovery circuits}

CPC - 2025.05

 Apparatus or processes for interconnecting storage elements, e.g. for threading magnetic cores

7/00	Arrangements for writing information into, or reading information out from, a digital store (G11C 5/00 takes precedence; auxiliary circuits for	7/1054 7/1057	 {Optical output buffers} {Data output buffers, e.g. comprising level conversion circuits, circuits for adapting load}
	stores using semiconductor devices G11C 11/4063,	7/106	• • • {Data output latches}
7/005	G11C 11/413) • {with combined beam-and individual cell access}	7/1063	{Control signal output circuits, e.g. status or
7/003	 with means for avoiding parasitic signals 	7/10//	busy flags, feedback command signals}
7/02	 with means for avoiding parasite signals with means for avoiding disturbances due to 	7/1066 7/1069	 {Output synchronization} {I/O lines read out arrangements}
7704	temperature effects	7/1009	{for memories with random access ports
7/06	 Sense amplifiers; Associated circuits {, e.g. timing or triggering circuits} 	7/1072	synchronised on clock signal pulse trains, e.g. synchronous memories, self timed memories}
7/062	• • {Differential amplifiers of non-latching type, e.g. comparators, long-tailed pairs}	7/1075	• • {for multiport memories each having random access ports and serial ports, e.g. video RAM}
7/065	• • {Differential amplifiers of latching type}	7/1078	• • {Data input circuits, e.g. write amplifiers, data
7/067	• • {Single-ended amplifiers}		input buffers, data input registers, data input level
7/08	Control thereof		conversion circuits}
7/10	 Input/output [I/O] data interface arrangements, e.g. I/O data control circuits, I/O data buffers 	7/1081 7/1084	 {Optical input buffers} {Data input buffers, e.g. comprising level
7/1003	• • {Interface circuits for daisy chain or ring bus		conversion circuits, circuits for adapting load}
	memory arrangements}	7/1087	{Data input latches}
7/1006	• • {Data managing, e.g. manipulating data before	7/109	{Control signal input circuits}
	writing or reading out, data bus switches or	7/1093	{Input synchronization}
7/1000	control circuits therefor}	7/1096	• • • {Write circuits, e.g. I/O line write drivers}
7/1009 7/1012	 • • {Data masking during input/output} • • {Data reordering during input/output, e.g. crossbars, layers of multiplexers, shifting or 	7/12	 Bit line control circuits, e.g. drivers, boosters, pull- up circuits, pull-down circuits, precharging circuits, equalising circuits, for bit lines
	rotating}	7/14	 Dummy cell management; Sense reference voltage
7/1015	• • {Read-write modes for single port memories, i.e.	//14	generators
	having either a random port or a serial port}	7/16	Storage of analogue signals in digital stores using
7/1018	• • • {Serial bit line access mode, e.g. using bit line address shift registers, bit line address counters, bit line burst counters}	,,10	an arrangement comprising analogue/digital [A/D] converters, digital memories and digital/analogue [D/A] converters
7/1021	• • • {Page serial bit line access mode, i.e. using	7/18	Bit line organisation; Bit line lay-out
	an enabled row address stroke pulse with its	7/20	Memory cell initialisation circuits, e.g. when
	associated word line address and a sequence	.,_0	powering up or down, memory clear, latent image
	of enabled column address stroke pulses each		memory
	with its associated bit line address}	7/22	 Read-write [R-W] timing or clocking circuits;
7/1024	• • • • Extended data output [EDO] mode, i.e.		Read-write [R-W] control signal generators or
	keeping output buffer enabled during an		management
7/1027	extended period of time} {Static column decode serial bit line access	7/222	• • {Clock generating, synchronizing or distributing
//102/	mode, i.e. using an enabled row address		circuits within memory device}
	stroke pulse with its associated word line	7/225	• • {Clock input buffers}
	address and a sequence of enabled bit line	7/227	• • {Timing of memory operations based on dummy
	addresses}	7/04	memory elements or replica circuits}
7/103	• • • {using serially addressed read-write data	7/24	 Memory cell safety or protection circuits, e.g. arrangements for preventing inadvertent reading or
	registers (G11C 7/1036 takes precedence)}		writing; Status cells; Test cells
7/1033	{ using data registers of which only one stage		witting, Status cens, Test cens
	is addressed for sequentially outputting data	8/00	Arrangements for selecting an address in a digital
	from a predetermined number of stages, e.g.		store (for stores using transistors <u>G11C 11/407</u> ,
	nibble read-write mode}		<u>G11C 11/413</u>)
7/1036	• • {using data shift registers}	8/005	• {with travelling wave access}
7/1039	• • • {using pipelining techniques, i.e. using latches between functional memory parts, e.g. row/	8/04	 using a sequential addressing device, e.g. shift register, counter
	column decoders, I/O buffers, sense amplifiers}	8/06	• Address interface arrangements, e.g. address buffers
7/1042	 • • {using interleaving techniques, i.e. read-write of one part of the memory while preparing another part} 	8/08	 Word line control circuits, e.g. drivers, boosters, pull-up circuits, pull-down circuits, precharging circuits, for word lines
7/1045	• • • {Read-write mode select circuits}	8/10	. Decoders
7/1048	 {Data bus control circuits, e.g. precharging, presetting, equalising} 	8/12	Group selection circuits, e.g. for memory block selection, chip selection, array selection
7/1051	• • {Data output circuits, e.g. read-out amplifiers, data output buffers, data output registers, data output level conversion circuits}	8/14	Word line organisation; Word line lay-out
	output to tel conversion encurs;		

8/16	 Multiple access memory array, e.g. addressing one storage element via at least two independent addressing line groups 	11/06085 {Multi-aperture structures or multi-magnetic closed circuits, each aperture storing a "bit", realised by rods, plates, grids, waffle-irons,(i.e.
8/18	 Address timing or clocking circuits; Address control 	grooved plates) or similar devices}
	signal generation or management, e.g. for row	11/06092 {Multi-aperture structures or multi-magnetic
	address strobe [RAS] or column address strobe [CAS] signals	closed circuits using two or more apertures per bit}
8/20	 Address safety or protection circuits, i.e. 	11/061 using elements with single aperture or magnetic
	arrangements for preventing unauthorized or	loop for storage, one element per bit, and for
	accidental access	destructive read-out {(contains no documents,
11/00	Digital stores characterised by the use of	see G11C 11/06007, G11C 11/06014,
11/00	particular electric or magnetic storage	<u>G11C 11/06021</u> , <u>G11C 11/06028</u>)}
	elements; Storage elements therefor	11/063 bit organised, such as 2 1/2D, 3D
	(G11C 14/00 - G11C 21/00 take precedence)	organisation, i.e. for selection of an element by means of at least two coincident
	NOTE	partial currents both for reading and for
		writing {(contains no documents; see
	Group G11C 11/56 takes precedence over groups	G11C 11/06035)}
	<u>G11C 11/02</u> - <u>G11C 11/54</u> .	11/065 word organised, such as 2D organisation, or
	{This Note corresponds to IPC Note (1) relating to	linear selection, i.e. for selection of all the
	<u>G11C 11/02</u> - <u>G11C 11/56</u> .}	elements of a word by means of a single full
11/005	• {comprising combined but independently operative	current for reading {(contains no documents;
11/003	RAM-ROM, RAM-PROM, RAM-EPROM cells}	see G11C 11/06042)}
11/02	 using magnetic elements 	11/067 using elements with single aperture or
11/04	• using storage elements having cylindrical form,	magnetic loop for storage, one element
	e.g. rod, wire (<u>G11C 11/12</u> , <u>G11C 11/14</u> take	per bit, and for non-destructive read-
	precedence)	out {(contains no documents, see
11/06	using single-aperture storage elements, e.g. ring	G11C 11/0605 - G11C 11/06071)} 11/08 • using multi-aperture storage elements, e.g.
	core; using multi-aperture plates in which each	using transfluxors; using plates incorporating
	individual aperture forms a storage element	several individual multi-aperture storage elements
11/06007	• • • {using a single aperture or single magnetic	(G11C 11/10 takes precedence)
	closed circuit}	11/10 using multi-axial storage elements
	<u>NOTE</u>	
	{Provisionally contains the following	11/12 using tensors; using twistors, i.e. elements in
		 11/12 . using tensors; using twistors, i.e. elements in which one axis of magnetisation is twisted 11/14 . using thin-film elements 11/15 . using multiple magnetic layers (G11C 11/155)
	{Provisionally contains the following details; control write -, read -, address circuitry (pulse generators in general H03K 5/00, H03K 17/00); arrangements for	 11/12 . using tensors; using twistors, i.e. elements in which one axis of magnetisation is twisted 11/14 . using thin-film elements 11/15 . using multiple magnetic layers (G11C 11/155 takes precedence)
	{Provisionally contains the following details; control write -, read -, address circuitry (pulse generators in general H03K 5/00, H03K 17/00); arrangements for temperature compensation; checking of the	 11/12 . using tensors; using twistors, i.e. elements in which one axis of magnetisation is twisted 11/14 . using thin-film elements 11/15 . using multiple magnetic layers (G11C 11/155 takes precedence) 11/155 . with cylindrical configuration
	{Provisionally contains the following details; control write -, read -, address circuitry (pulse generators in general H03K 5/00, H03K 17/00); arrangements for temperature compensation; checking of the correct functioning and repair arrangements	 11/12 . using tensors; using twistors, i.e. elements in which one axis of magnetisation is twisted 11/14 . using thin-film elements 11/15 . using multiple magnetic layers (G11C 11/155 takes precedence) 11/155 . with cylindrical configuration 11/16 . using elements in which the storage effect is
	{Provisionally contains the following details; control write -, read -, address circuitry (pulse generators in general H03K 5/00, H03K 17/00); arrangements for temperature compensation; checking of the correct functioning and repair arrangements (checking methods in general G06F 11/00,	 11/12 . using tensors; using twistors, i.e. elements in which one axis of magnetisation is twisted 11/14 . using thin-film elements 11/15 . using multiple magnetic layers (G11C 11/155 takes precedence) 11/155 . with cylindrical configuration 11/16 . using elements in which the storage effect is based on magnetic spin effect
	{Provisionally contains the following details; control write -, read -, address circuitry (pulse generators in general H03K 5/00, H03K 17/00); arrangements for temperature compensation; checking of the correct functioning and repair arrangements (checking methods in general G06F 11/00, G06F 11/28; testing magnetic elements	 11/12 . using tensors; using twistors, i.e. elements in which one axis of magnetisation is twisted 11/14 . using thin-film elements 11/15 . using multiple magnetic layers (G11C 11/155 takes precedence) 11/155 . with cylindrical configuration 11/16 . using elements in which the storage effect is based on magnetic spin effect 11/161 {details concerning the memory cell structure,
	{Provisionally contains the following details; control write -, read -, address circuitry (pulse generators in general H03K 5/00, H03K 17/00); arrangements for temperature compensation; checking of the correct functioning and repair arrangements (checking methods in general G06F 11/00, G06F 11/28; testing magnetic elements per seG01R 33/00); magnetic properties,	 11/12 . using tensors; using twistors, i.e. elements in which one axis of magnetisation is twisted 11/14 . using thin-film elements 11/15 . using multiple magnetic layers (G11C 11/155 takes precedence) 11/155 . with cylindrical configuration 11/16 . using elements in which the storage effect is based on magnetic spin effect 11/161 . {details concerning the memory cell structure, e.g. the layers of the ferromagnetic memory
	{Provisionally contains the following details; control write -, read -, address circuitry (pulse generators in general H03K 5/00, H03K 17/00); arrangements for temperature compensation; checking of the correct functioning and repair arrangements (checking methods in general G06F 11/00, G06F 11/28; testing magnetic elements	 11/12 . using tensors; using twistors, i.e. elements in which one axis of magnetisation is twisted 11/14 . using thin-film elements 11/15 . using multiple magnetic layers (G11C 11/155 takes precedence) 11/155 . with cylindrical configuration 11/16 . using elements in which the storage effect is based on magnetic spin effect 11/161 . {details concerning the memory cell structure, e.g. the layers of the ferromagnetic memory cell}
11.05014	{Provisionally contains the following details; control write -, read -, address circuitry (pulse generators in general H03K 5/00, H03K 17/00); arrangements for temperature compensation; checking of the correct functioning and repair arrangements (checking methods in general G06F 11/00, G06F 11/28; testing magnetic elements per seG01R 33/00); magnetic properties, choice of materials or the like (materials per seH01F 1/00)	 11/12 . using tensors; using twistors, i.e. elements in which one axis of magnetisation is twisted 11/14 . using thin-film elements 11/15 . using multiple magnetic layers (G11C 11/155 takes precedence) 11/155 . with cylindrical configuration 11/16 . using elements in which the storage effect is based on magnetic spin effect 11/161 {details concerning the memory cell structure, e.g. the layers of the ferromagnetic memory cell} 11/165 {Auxiliary circuits}
	{Provisionally contains the following details; control write -, read -, address circuitry (pulse generators in general H03K 5/00, H03K 17/00); arrangements for temperature compensation; checking of the correct functioning and repair arrangements (checking methods in general G06F 11/00, G06F 11/28; testing magnetic elements per seG01R 33/00); magnetic properties, choice of materials or the like (materials per seH01F 1/00)}	 11/12 . using tensors; using twistors, i.e. elements in which one axis of magnetisation is twisted 11/14 . using thin-film elements 11/15 . using multiple magnetic layers (G11C 11/155 takes precedence) 11/155 . with cylindrical configuration 11/16 . using elements in which the storage effect is based on magnetic spin effect 11/161 {details concerning the memory cell structure, e.g. the layers of the ferromagnetic memory cell} 11/165 {Auxiliary circuits} 11/1653 {Address circuits or decoders}
11/06021	{Provisionally contains the following details; control write -, read -, address circuitry (pulse generators in general H03K 5/00, H03K 17/00); arrangements for temperature compensation; checking of the correct functioning and repair arrangements (checking methods in general G06F 11/00, G06F 11/28; testing magnetic elements per seG01R 33/00); magnetic properties, choice of materials or the like (materials per seH01F 1/00)} {using one such element per bit} {with destructive read-out}	 11/12 . using tensors; using twistors, i.e. elements in which one axis of magnetisation is twisted 11/14 . using thin-film elements 11/15 . using multiple magnetic layers (G11C 11/155 takes precedence) 11/155 . with cylindrical configuration 11/16 . using elements in which the storage effect is based on magnetic spin effect 11/161 . {details concerning the memory cell structure, e.g. the layers of the ferromagnetic memory cell} 11/165 {Auxiliary circuits} 11/1653 {Address circuits or decoders} 11/1655 {Bit-line or column circuits}
11/06021 11/06028	{Provisionally contains the following details; control write -, read -, address circuitry (pulse generators in general H03K 5/00, H03K 17/00); arrangements for temperature compensation; checking of the correct functioning and repair arrangements (checking methods in general G06F 11/00, G06F 11/28; testing magnetic elements per seG01R 33/00); magnetic properties, choice of materials or the like (materials per seH01F 1/00) } {using one such element per bit} {with destructive read-out}	 11/12 . using tensors; using twistors, i.e. elements in which one axis of magnetisation is twisted 11/14 . using thin-film elements 11/15 . using multiple magnetic layers (G11C 11/155 takes precedence) 11/155 . with cylindrical configuration 11/16 . using elements in which the storage effect is based on magnetic spin effect 11/161 . {details concerning the memory cell structure, e.g. the layers of the ferromagnetic memory cell} 11/165 {Auxiliary circuits} 11/1653 {Address circuits or decoders} 11/1655 {Bit-line or column circuits} 11/1657 {Word-line or row circuits}
11/06021 11/06028	{Provisionally contains the following details; control write -, read -, address circuitry (pulse generators in general H03K 5/00, H03K 17/00); arrangements for temperature compensation; checking of the correct functioning and repair arrangements (checking methods in general G06F 11/00, G06F 11/28; testing magnetic elements per seG01R 33/00); magnetic properties, choice of materials or the like (materials per seH01F 1/00) } {using one such element per bit} {with destructive read-out} {Matrixes} {Bit core selection for writing or	 11/12 . using tensors; using twistors, i.e. elements in which one axis of magnetisation is twisted 11/14 . using thin-film elements 11/15 . using multiple magnetic layers (G11C 11/155 takes precedence) 11/155 . with cylindrical configuration 11/16 . using elements in which the storage effect is based on magnetic spin effect 11/161 . {details concerning the memory cell structure, e.g. the layers of the ferromagnetic memory cell} 11/165 {Auxiliary circuits} 11/1653 {Address circuits or decoders} 11/1655 {Bit-line or column circuits} 11/1657 {Word-line or row circuits} 11/1659 {Cell access}
11/06021 11/06028	{Provisionally contains the following details; control write -, read -, address circuitry (pulse generators in general H03K 5/00, H03K 17/00); arrangements for temperature compensation; checking of the correct functioning and repair arrangements (checking methods in general G06F 11/00, G06F 11/28; testing magnetic elements per seG01R 33/00); magnetic properties, choice of materials or the like (materials per seH01F 1/00) } {using one such element per bit} {Matrixes} {Bit core selection for writing or reading, by at least two coincident	 11/12 . using tensors; using twistors, i.e. elements in which one axis of magnetisation is twisted 11/14 . using thin-film elements 11/15 . using multiple magnetic layers (G11C 11/155 takes precedence) 11/155 . with cylindrical configuration 11/16 . using elements in which the storage effect is based on magnetic spin effect 11/161 . {details concerning the memory cell structure, e.g. the layers of the ferromagnetic memory cell} 11/165 {Auxiliary circuits} 11/1653 {Address circuits or decoders} 11/1655 {Bit-line or column circuits} 11/1657 {Word-line or row circuits}
11/06021 11/06028	{Provisionally contains the following details; control write -, read -, address circuitry (pulse generators in general H03K 5/00, H03K 17/00); arrangements for temperature compensation; checking of the correct functioning and repair arrangements (checking methods in general G06F 11/00, G06F 11/28; testing magnetic elements per seG01R 33/00); magnetic properties, choice of materials or the like (materials per seH01F 1/00) } {using one such element per bit} {Matrixes} {Bit core selection for writing or reading, by at least two coincident partial currents, e.g. "bit"- organised,	 11/12 . using tensors; using twistors, i.e. elements in which one axis of magnetisation is twisted 11/14 . using thin-film elements 11/15 . using multiple magnetic layers (G11C 11/155 takes precedence) 11/155 with cylindrical configuration 11/16 . using elements in which the storage effect is based on magnetic spin effect 11/161 {details concerning the memory cell structure, e.g. the layers of the ferromagnetic memory cell} 11/165 {Auxiliary circuits} 11/1653 {Address circuits or decoders} 11/1657 {Bit-line or column circuits} 11/1659 {Cell access} 11/1673 {Reading or sensing circuits or methods}
11/06021 11/06028 11/06035	{Provisionally contains the following details; control write -, read -, address circuitry (pulse generators in general H03K 5/00, H03K 17/00); arrangements for temperature compensation; checking of the correct functioning and repair arrangements (checking methods in general G06F 11/00, G06F 11/28; testing magnetic elements per seG01R 33/00); magnetic properties, choice of materials or the like (materials per seH01F 1/00) } {with destructive read-out} {Matrixes} {Bit core selection for writing or reading, by at least two coincident partial currents, e.g. "bit"- organised, 2L/2D, or 3D}	 11/12 . using tensors; using twistors, i.e. elements in which one axis of magnetisation is twisted 11/14 . using thin-film elements 11/15 . using multiple magnetic layers (G11C 11/155 takes precedence) 11/155 with cylindrical configuration 11/16 . using elements in which the storage effect is based on magnetic spin effect 11/161 {details concerning the memory cell structure, e.g. the layers of the ferromagnetic memory cell} 11/165 {Auxiliary circuits} 11/1653 {Address circuits or decoders} 11/1655 {Bit-line or column circuits} 11/1657 {Word-line or row circuits} 11/1659 {Cell access} 11/1673 {Reading or sensing circuits or methods} 11/1675 {Writing or programming circuits or
11/06021 11/06028 11/06035	{Provisionally contains the following details; control write -, read -, address circuitry (pulse generators in general H03K 5/00, H03K 17/00); arrangements for temperature compensation; checking of the correct functioning and repair arrangements (checking methods in general G06F 11/00, G06F 11/28; testing magnetic elements per seG01R 33/00); magnetic properties, choice of materials or the like (materials per seH01F 1/00) } {using one such element per bit} {Matrixes} {Bit core selection for writing or reading, by at least two coincident partial currents, e.g. "bit"- organised,	 11/12 . using tensors; using twistors, i.e. elements in which one axis of magnetisation is twisted 11/14 . using thin-film elements 11/15 . using multiple magnetic layers (G11C 11/155 takes precedence) 11/155 . with cylindrical configuration 11/16 . using elements in which the storage effect is based on magnetic spin effect 11/161 . {details concerning the memory cell structure, e.g. the layers of the ferromagnetic memory cell} 11/165 . {Auxiliary circuits} 11/1653 {Address circuits or decoders} 11/1655 {Bit-line or column circuits} 11/1657 {Word-line or row circuits} 11/1659 {Cell access} 11/1673 {Reading or sensing circuits or methods} 11/1675 {Writing or programming circuits or methods} 11/1677 {Verifying circuits or methods} 11/1693 {Timing circuits or methods}
11/06021 11/06028 11/06035	{Provisionally contains the following details; control write -, read -, address circuitry (pulse generators in general H03K 5/00, H03K 17/00); arrangements for temperature compensation; checking of the correct functioning and repair arrangements (checking methods in general G06F 11/00, G06F 11/28; testing magnetic elements per seG01R 33/00); magnetic properties, choice of materials or the like (materials per seH01F 1/00) } {using one such element per bit} {with destructive read-out} {Matrixes} {Bit core selection for writing or reading, by at least two coincident partial currents, e.g. "bit"- organised, 2L/2D, or 3D} {"word"-organised, e.g. 2D organisation or linear selection, i.e. full current selection through all the	11/12 . using tensors; using twistors, i.e. elements in which one axis of magnetisation is twisted 11/14 . using thin-film elements 11/15 . using multiple magnetic layers (G11C 11/155 takes precedence) 11/15 . with cylindrical configuration 11/16 . using elements in which the storage effect is based on magnetic spin effect 11/161 . {details concerning the memory cell structure, e.g. the layers of the ferromagnetic memory cell} 11/165 {Auxiliary circuits} 11/1653 {Address circuits or decoders} 11/1655 {Bit-line or column circuits} 11/1657 {Word-line or row circuits} 11/1659 {Cell access} 11/1673 {Reading or sensing circuits or methods} 11/1675 {Writing or programming circuits or methods} 11/1677 {Verifying circuits or methods} 11/1693 {Timing circuits or methods} 11/1695 {Protection circuits or methods}
11/06021 11/06028 11/06035 11/06042	{Provisionally contains the following details; control write -, read -, address circuitry (pulse generators in general H03K 5/00, H03K 17/00); arrangements for temperature compensation; checking of the correct functioning and repair arrangements (checking methods in general G06F 11/00, G06F 11/28; testing magnetic elements per seG01R 33/00); magnetic properties, choice of materials or the like (materials per seH01F 1/00) } {using one such element per bit} {With destructive read-out} {Bit core selection for writing or reading, by at least two coincident partial currents, e.g. "bit"- organised, 2L/2D, or 3D} {"word"-organised, e.g. 2D organisation or linear selection, i.e. full current selection through all the bit-cores of a word during reading}	 11/12 . using tensors; using twistors, i.e. elements in which one axis of magnetisation is twisted 11/14 . using thin-film elements 11/15 . using multiple magnetic layers (G11C 11/155 takes precedence) 11/155 . with cylindrical configuration 11/16 . using elements in which the storage effect is based on magnetic spin effect 11/161 . {details concerning the memory cell structure, e.g. the layers of the ferromagnetic memory cell} 11/165 . {Auxiliary circuits} 11/1653 {Address circuits or decoders} 11/1655 {Bit-line or column circuits} 11/1657 {Word-line or row circuits} 11/1659 {Cell access} 11/1673 {Reading or sensing circuits or methods} 11/1675 {Writing or programming circuits or methods} 11/1677 {Verifying circuits or methods} 11/1693 {Timing circuits or methods}
11/06021 11/06028 11/06035 11/06042 11/0605	{Provisionally contains the following details; control write -, read -, address circuitry (pulse generators in general H03K 5/00, H03K 17/00); arrangements for temperature compensation; checking of the correct functioning and repair arrangements (checking methods in general G06F 11/00, G06F 11/28; testing magnetic elements per seG01R 33/00); magnetic properties, choice of materials or the like (materials per seH01F 1/00) } {using one such element per bit} {Matrixes} {Bit core selection for writing or reading, by at least two coincident partial currents, e.g. "bit"- organised, 2L/2D, or 3D} {"word"-organised, e.g. 2D organisation or linear selection, i.e. full current selection through all the bit-cores of a word during reading} {with non-destructive read-out}	11/12 . using tensors; using twistors, i.e. elements in which one axis of magnetisation is twisted 11/14 . using thin-film elements 11/15 . using multiple magnetic layers (G11C 11/155 takes precedence) 11/15 . with cylindrical configuration 11/16 . using elements in which the storage effect is based on magnetic spin effect 11/161 . {details concerning the memory cell structure, e.g. the layers of the ferromagnetic memory cell} 11/165 {Auxiliary circuits} 11/1653 {Address circuits or decoders} 11/1655 {Bit-line or column circuits} 11/1657 {Word-line or row circuits} 11/1659 {Cell access} 11/1673 {Reading or sensing circuits or methods} 11/1675 {Writing or programming circuits or methods} 11/1677 {Verifying circuits or methods} 11/1693 {Timing circuits or methods} 11/1695 {Protection circuits or methods}
11/06021 11/06028 11/06035 11/06042 11/0605 11/06057	{Provisionally contains the following details; control write -, read -, address circuitry (pulse generators in general H03K 5/00, H03K 17/00); arrangements for temperature compensation; checking of the correct functioning and repair arrangements (checking methods in general G06F 11/00, G06F 11/28; testing magnetic elements per seG01R 33/00); magnetic properties, choice of materials or the like (materials per seH01F 1/00) } {using one such element per bit} {Matrixes} {Bit core selection for writing or reading, by at least two coincident partial currents, e.g. "bit"- organised, 2L/2D, or 3D} {"word"-organised, e.g. 2D organisation or linear selection, i.e. full current selection through all the bit-cores of a word during reading} {Matrixes}	11/12 . using tensors; using twistors, i.e. elements in which one axis of magnetisation is twisted 11/14 . using thin-film elements 11/15 . using multiple magnetic layers (G11C 11/155 takes precedence) 11/15 . with cylindrical configuration 11/16 . using elements in which the storage effect is based on magnetic spin effect 11/161 . {details concerning the memory cell structure, e.g. the layers of the ferromagnetic memory cell} 11/165 . {Auxiliary circuits} 11/1653 {Address circuits or decoders} 11/1655 {Bit-line or column circuits} 11/1657 {Word-line or row circuits} 11/1659 {Cell access} 11/1670 {Reading or sensing circuits or methods} 11/1671 {Verifying circuits or methods} 11/1693 {Timing circuits or methods} 11/1694 {Protection circuits or methods} 11/18 . using Hall-effect devices 11/19 . using non-linear reactive devices in resonant circuits
11/06021 11/06028 11/06035 11/06042 11/0605	{Provisionally contains the following details; control write -, read -, address circuitry (pulse generators in general H03K 5/00, H03K 17/00); arrangements for temperature compensation; checking of the correct functioning and repair arrangements (checking methods in general G06F 11/00, G06F 11/28; testing magnetic elements per seG01R 33/00); magnetic properties, choice of materials or the like (materials per seH01F 1/00) } {using one such element per bit} {With destructive read-out} {Bit core selection for writing or reading, by at least two coincident partial currents, e.g. "bit"- organised, 2L/2D, or 3D} {"word"-organised, e.g. 2D organisation or linear selection, i.e. full current selection through all the bit-cores of a word during reading} {Watrixes} {Matrixes} {"bit"-organised (2 1/2D, 3D or	11/12 using tensors; using twistors, i.e. elements in which one axis of magnetisation is twisted 11/14 using thin-film elements 11/15 using multiple magnetic layers (G11C 11/155 takes precedence) 11/15 with cylindrical configuration 11/16 . using elements in which the storage effect is based on magnetic spin effect 11/161 {details concerning the memory cell structure, e.g. the layers of the ferromagnetic memory cell} 11/165 {Auxiliary circuits} 11/1653 {Address circuits or decoders} 11/1655 {Bit-line or column circuits} 11/1657 {Word-line or row circuits} 11/1659 {Cell access} 11/1673 {Reading or sensing circuits or methods} 11/1675 {Writing or programming circuits or methods} 11/1676 {Verifying circuits or methods} 11/1697 {Protection circuits or methods} 11/1697 {Protection circuits or methods} 11/18 . using Hall-effect devices 11/19 . using non-linear reactive devices in resonant circuits 11/20 . using parametrons
11/06021 11/06028 11/06035 11/06042 11/0605 11/06057 11/06064	{Provisionally contains the following details; control write -, read -, address circuitry (pulse generators in general H03K 5/00, H03K 17/00); arrangements for temperature compensation; checking of the correct functioning and repair arrangements (checking methods in general G06F 11/00, G06F 11/28; testing magnetic elements per seG01R 33/00); magnetic properties, choice of materials or the like (materials per seH01F 1/00) } {using one such element per bit} {With destructive read-out} {Matrixes} {Bit core selection for writing or reading, by at least two coincident partial currents, e.g. "bit"- organised, 2L/2D, or 3D} {"word"-organised, e.g. 2D organisation or linear selection, i.e. full current selection through all the bit-cores of a word during reading} {With non-destructive read-out} {Matrixes} {"bit"-organised (2 1/2D, 3D or similar organisation)}	11/12 . using tensors; using twistors, i.e. elements in which one axis of magnetisation is twisted 11/14 . using thin-film elements 11/15 . using multiple magnetic layers (G11C 11/155 takes precedence) 11/15 . with cylindrical configuration 11/16 . using elements in which the storage effect is based on magnetic spin effect 11/161 . {details concerning the memory cell structure, e.g. the layers of the ferromagnetic memory cell} 11/165 {Auxiliary circuits} 11/1653 {Address circuits or decoders} 11/1655 {Bit-line or column circuits} 11/1657 {Word-line or row circuits} 11/1679 {Cell access} 11/1670 {Writing or programming circuits or methods} 11/1671 {Writing circuits or methods} 11/1672 {Timing circuits or methods} 11/1673 {Protection circuits or methods} 11/1694 {Power supply circuits} 11/1695 {Power supply circuits} 11/18 . using Hall-effect devices 11/19 . using parametrons 11/20 . using parametrons 11/21 . using electric elements
11/06021 11/06028 11/06035 11/06042 11/0605 11/06057 11/06064	{Provisionally contains the following details; control write -, read -, address circuitry (pulse generators in general H03K 5/00, H03K 17/00); arrangements for temperature compensation; checking of the correct functioning and repair arrangements (checking methods in general G06F 11/00, G06F 11/28; testing magnetic elements per seG01R 33/00); magnetic properties, choice of materials or the like (materials per seH01F 1/00) } {using one such element per bit} {Matrixes} {Bit core selection for writing or reading, by at least two coincident partial currents, e.g. "bit"- organised, 2L/2D, or 3D} {"word"-organised, e.g. 2D organisation or linear selection, i.e. full current selection through all the bit-cores of a word during reading} {Matrixes} {mith non-destructive read-out} {Matrixes} {"bit"-organised (2 1/2D, 3D or similar organisation)} {"word"-organised (2D organisation	11/12 . using tensors; using twistors, i.e. elements in which one axis of magnetisation is twisted 11/14 . using thin-film elements 11/15 . using multiple magnetic layers (G11C 11/155 takes precedence) 11/155 with cylindrical configuration 11/16 . using elements in which the storage effect is based on magnetic spin effect 11/161 {details concerning the memory cell structure, e.g. the layers of the ferromagnetic memory cell} 11/165 {Auxiliary circuits} 11/1653 {Address circuits or decoders} 11/1655 {Bit-line or column circuits} 11/1657 {Word-line or row circuits} 11/1659 {Cell access} 11/1673 {Reading or sensing circuits or methods} 11/1675 {Writing or programming circuits or methods} 11/1676 {Verifying circuits or methods} 11/1693 {Timing circuits or methods} 11/1694 {Protection circuits or methods} 11/1695 {Power supply circuits} 11/18 . using Hall-effect devices 11/19 . using parametrons 11/21 . using electric elements 11/22 . using ferroelectric elements
11/06021 11/06028 11/06035 11/06042 11/0605 11/06057 11/06064 11/06071	{Provisionally contains the following details; control write -, read -, address circuitry (pulse generators in general H03K 5/00, H03K 17/00); arrangements for temperature compensation; checking of the correct functioning and repair arrangements (checking methods in general G06F 11/00, G06F 11/28; testing magnetic elements per seG01R 33/00); magnetic properties, choice of materials or the like (materials per seH01F 1/00) } { using one such element per bit } { With destructive read-out } { Matrixes } { Bit core selection for writing or reading, by at least two coincident partial currents, e.g. "bit"- organised, 2L/2D, or 3D } { "word"-organised, e.g. 2D organisation or linear selection, i.e. full current selection through all the bit-cores of a word during reading } { With non-destructive read-out } { Matrixes } { "bit"-organised (2 1/2D, 3D or similar organisation) } { "word"-organised (2D organisation or linear selection) }	11/12 using tensors; using twistors, i.e. elements in which one axis of magnetisation is twisted 11/14 using thin-film elements 11/15 using multiple magnetic layers (G11C 11/155 takes precedence) 11/155 with cylindrical configuration 11/16 using elements in which the storage effect is based on magnetic spin effect 11/161 {details concerning the memory cell structure, e.g. the layers of the ferromagnetic memory cell} 11/165 {Auxiliary circuits} 11/1653 {Address circuits or decoders} 11/1655 {Bit-line or column circuits} 11/1657 {Word-line or row circuits} 11/1659 {Cell access} 11/1670 {Reading or sensing circuits or methods} 11/1671 {Writing or programming circuits or methods} 11/1693 {Timing circuits or methods} 11/1695 {Protection circuits or methods} 11/1697 {Power supply circuits} 11/18 using Hall-effect devices 11/19 .using non-linear reactive devices in resonant circuits 11/20 . using parametrons 11/21 .using electric elements 11/22 .using ferroelectric elements 11/22 .using ferroelectric capacitors}
11/06021 11/06028 11/06035 11/06042 11/0605 11/06057 11/06064 11/06071	{Provisionally contains the following details; control write -, read -, address circuitry (pulse generators in general H03K 5/00, H03K 17/00); arrangements for temperature compensation; checking of the correct functioning and repair arrangements (checking methods in general G06F 11/00, G06F 11/28; testing magnetic elements per seG01R 33/00); magnetic properties, choice of materials or the like (materials per seH01F 1/00) } {using one such element per bit} {Matrixes} {Bit core selection for writing or reading, by at least two coincident partial currents, e.g. "bit"- organised, 2L/2D, or 3D} {"word"-organised, e.g. 2D organisation or linear selection, i.e. full current selection through all the bit-cores of a word during reading} {Matrixes} {mith non-destructive read-out} {Matrixes} {"bit"-organised (2 1/2D, 3D or similar organisation)} {"word"-organised (2D organisation	11/12 . using tensors; using twistors, i.e. elements in which one axis of magnetisation is twisted 11/14 . using thin-film elements 11/15 . using multiple magnetic layers (G11C 11/155 takes precedence) 11/155 with cylindrical configuration 11/16 . using elements in which the storage effect is based on magnetic spin effect 11/161 {details concerning the memory cell structure, e.g. the layers of the ferromagnetic memory cell} 11/165 {Auxiliary circuits} 11/1653 {Address circuits or decoders} 11/1655 {Bit-line or column circuits} 11/1657 {Word-line or row circuits} 11/1659 {Cell access} 11/1673 {Reading or sensing circuits or methods} 11/1675 {Writing or programming circuits or methods} 11/1676 {Verifying circuits or methods} 11/1693 {Timing circuits or methods} 11/1694 {Protection circuits or methods} 11/1695 {Power supply circuits} 11/18 . using Hall-effect devices 11/19 . using parametrons 11/21 . using electric elements 11/22 . using ferroelectric elements

11/225	• • {Auxiliary circuits}	11/40618 {Refresh operations over multiple banks
11/2253	{Address circuits or decoders}	or interleaving}
11/2255	{Bit-line or column circuits}	11/40622 {Partial refresh of memory arrays}
11/2257	• • • • {Word-line or row circuits}	11/40626 {Temperature related aspects of refresh
11/2259	{Cell access}	operations}
11/2273	• • • {Reading or sensing circuits or methods}	11/4063 Auxiliary circuits, e.g. for addressing,
11/2275	• • • • {Writing or programming circuits or	decoding, driving, writing, sensing or
	methods}	timing
11/2277	• • • {Verifying circuits or methods}	11/4067 for memory cells of the bipolar type
11/2293	• • • {Timing circuits or methods}	11/407 for memory cells of the field-effect type 11/4072 Circuits for initialization, powering
11/2295	{Protection circuits or methods}	up or down, clearing memory or
11/2297	· · · · {Power supply circuits}	presetting
11/23	using electrostatic storage on a common	11/4074 Power supply or voltage generation
	layer, e.g. Forrester-Haeff tubes {or William tubes}(G11C 11/22 takes precedence)	circuits, e.g. bias voltage generators,
11/24	• using capacitors (G11C 11/22 takes precedence;	substrate voltage generators, back-up
11/2-	using a combination of semiconductor devices	power, power control circuits
	and capacitors <u>G11C 11/34</u> , e.g. <u>G11C 11/40</u>)	11/4076 Timing circuits (for regeneration
11/26	using discharge tubes	management <u>G11C 11/406</u>)
11/265	• • • {counting tubes, e.g. decatrons or trochotrons}	11/4078 Safety or protection circuits, e.g.
11/28	using gas-filled tubes	for preventing inadvertent or unauthorised reading or writing;
11/30	• • • using vacuum tubes (<u>G11C 11/23</u> takes	Status cells; Test cells (protection of
	precedence)	memory contents during checking or
11/34	using semiconductor devices	testing <u>G11C 29/52</u>)
11/35	• • • with charge storage in a depletion layer, e.g.	11/408 Address circuits
11/26	charge coupled devices using diodes, e.g. as threshold elements	11/4082 {Address Buffers; level conversion
11/36	{, i.e. diodes assuming a stable ON-stage	circuits}
	when driven above their threshold (S- or N-	11/4085 {Word line control circuits, e.g.
	characteristic)}	word line drivers, - boosters, - pull- up, - pull-down, - precharge}
11/38	using tunnel diodes	11/4087 {Address decoders, e.g. bit - or
11/39	using thyristors {or the avalanche or negative	word line decoders; Multiple line
	resistance type, e.g. PNPN, SCR, SCS, UJT}	decoders}
11/40	using transistors	11/409 Read-write [R-W] circuits
11/401	forming cells needing refreshing or charge	11/4091 Sense or sense/refresh amplifiers,
11/400	regeneration, i.e. dynamic cells	or associated sense circuitry, e.g.
11/402	with charge regeneration individual to each memory cell, i.e. internal refresh	for coupled bit-line precharging,
11/4023	• • • • • {using field effect transistors}	equalising or isolating 11/4093 Input/output [I/O] data interface
11/4026	{using bipolar transistors}	arrangements, e.g. data buffers
11/403	• • • • with charge regeneration common to a	11/4094 Bit-line management or control
	multiplicity of memory cells, i.e. external	circuits
	refresh	11/4096 Input/output [I/O] data management
11/404	• • • • with one charge-transfer gate, e.g. MOS	or control circuits, e.g. reading or
44/4045	transistor, per cell	writing circuits, I/O drivers or bit-
11/4045	(using a plurality of serially	line switches
	connected access transistors, each having a storage capacitor}	11/4097 Bit-line organisation, e.g. bit-line layout, folded bit lines
11/405	• • • • • with three charge-transfer gates, e.g.	11/4099 Dummy cell treatment; Reference
11/105	MOS transistors, per cell	voltage generators
11/406	Management or control of the refreshing	11/41 forming {static} cells with positive feedback,
	or charge-regeneration cycles	i.e. cells not needing refreshing or charge
11/40603	• • • • • {Arbitration, priority and concurrent	regeneration, e.g. bistable multivibrator or
	access to memory cells for read/write or	Schmitt trigger
11/40/05	refresh operations}	11/411 using bipolar transistors only
11/40607	• • • • • {Refresh operations in memory devices with an internal cache or data buffer}	11/4113 {with at least one cell access to base
11/40611	• • • • • {External triggering or timing of	or collector of at least one of said transistors, e.g. via access diodes, access
11/70011	internal or partially internal refresh	transistors {
	operations, e.g. auto-refresh or CAS-	11/4116 {with at least one cell access via
	before-RAS triggered refresh}	separately connected emittors of said
11/40615		transistors or via multiple emittors, e.g.
	e.g. hidden refresh, self refresh, pseudo-	T2L, ECL}
	SRAMs}	11/412 using field-effect transistors only

	(2 11)	10/001
11/4125	• • • • • {Cells incorporating circuit means for protecting against loss of information}	13/0014 {comprising cells based on organic memory material}
11/413	Auxiliary circuits, e.g. for addressing,	13/0016 {comprising polymers}
	decoding, driving, writing, sensing, timing	13/0019 {comprising bio-molecules}
	or power reduction	13/0021 {Auxiliary circuits}
11/414	• • • • • for memory cells of the bipolar type	13/0023 {Address circuits or decoders}
11/415	Address circuits	13/0026 {Bit-line or column circuits}
11/416	Read-write [R-W] circuits	13/0028 {Word-line or row circuits}
11/417	for memory cells of the field-effect type	13/003 {Cell access}
11/418	Address circuits	13/0033 {Disturbance prevention or evaluation;
11/419	Read-write [R-W] circuits	Refreshing of disturbed memory data}
11/42	using opto-electronic devices, i.e. light-emitting and photoelectric devices electrically- or	13/0035 • • • {Evaluating degradation, retention or wearout, e.g. by counting writing cycles}
11/44	optically- coupled {or feedback-coupled}	13/0038 {Power supply circuits}
11/44	• using super-conductive elements, e.g. cryotron	13/004 • • • {Reading or sensing circuits or methods}
11/46	• using thermoplastic elements	2013/0042 {Read using differential sensing, e.g. bit line
11/48	• using displaceable coupling elements, e.g.	[BL] and bit line bar [BLB]}
	ferromagnetic cores, to produce change between different states of mutual or self-inductance	2013/0045 {Read using current through the cell}
	{(contains no documents; see G11C 17/00 and	2013/0047 {Read destroying or disturbing the data}
	subgroups)}	2013/005 {Read using potential difference applied
11/50	using actuation of electric contacts to store the	between cell electrodes}
11/30	information	2013/0052 {Read process characterized by the shape,
11/52	using electromagnetic relays	e.g. form, length, amplitude of the read
11/54	 using elements simulating biological cells, e.g. 	pulse}
11/54	neuron	2013/0054 {Read is performed on a reference element,
11/56	 using storage elements with more than two stable 	e.g. cell, and the reference sensed value is used to compare the sensed value of the
	states represented by steps, e.g. of voltage, current,	selected cell}
	phase, frequency	2013/0057 {Read done in two steps, e.g. wherein the
11/5607	{using magnetic storage elements}	cell is read twice and one of the two read
11/5614	• • {using conductive bridging RAM [CBRAM] or	values serving as a reference value}
	programming metallization cells [PMC]}	13/0059 {Security or protection circuits or methods}
11/5621	• • {using charge storage in a floating gate}	13/0061 {Timing circuits or methods}
11/5628	{Programming or writing circuits; Data input	13/0064 {Verifying circuits or methods}
	circuits}	2013/0066 • • • • {Verify correct writing whilst writing is in
11/5635	• • • {Erasing circuits}	progress, e.g. by detecting onset or cessation
11/5642	• • • {Sensing or reading circuits; Data output	of current flow in cell and using the detector
	circuits}	output to terminate writing}
11/565	• • {using capacitive charge storage elements}	13/0069 {Writing or programming circuits or methods}
11/5657	• • {using ferroelectric storage elements}	2013/0071 {Write using write potential applied to access
11/5664	• • {using organic memory material storage	device gate}
	elements}	2013/0073 • • • • {Write using bi-directional cell biasing}
11/5671	• • {using charge trapping in an insulator}	2013/0076 {Write operation performed depending on
11/5678	• • {using amorphous/crystalline phase transition	read result}
	storage elements}	2013/0078 {Write using current through the cell}
11/5685	• • {using storage elements comprising metal oxide	2013/008 {Write by generating heat in the
	memory material, e.g. perovskites}	surroundings of the memory material, e.g.
11/5692	• • {read-only digital stores using storage elements	thermowrite}
	with more than two stable states}	2013/0083 Write to perform initialising, forming
13/00	Digital stores characterised by the use of storage	process, electro forming or conditioning}
	elements not covered by groups G11C 11/00,	2013/0085 {Write a page or sector of information
	G11C 23/00, or G11C 25/00	simultaneously, e.g. a complete row or word
13/0002	• {using resistive RAM [RRAM] elements}	line}
13/0004	• • {comprising amorphous/crystalline phase	2013/0088 {Write with the simultaneous writing of a
	transition cells}	plurality of cells} 2013/009 {Write using potential difference applied
13/0007	• • {comprising metal oxide memory material, e.g.	2013/009 {Write using potential difference applied between cell electrodes}
13/0009	perovskites} {RRAM elements whose operation depends upon	2013/0092 Write characterized by the shape, e.g. form,
13/0009	chemical change}	length, amplitude of the write pulse}
13/0011	{comprising conductive bridging RAM	2013/0095 {Write using strain induced by, e.g.
	[CBRAM] or programming metallization cells	piezoelectric, thermal effects}
	[PMCs]}	13/0097 • • • {Erasing, e.g. resetting, circuits or methods}

12/02		1.6/0.400	(
13/02	• using elements whose operation depends	16/0408	• • • {comprising cells containing floating gate
	upon chemical change {(G11C 13/0009 takes		transistors (<u>G11C 16/0483</u> , <u>G11C 16/0491</u> take
12/025	precedence)}	1.6/0.41.6	precedence)}
13/025	• • {using fullerenes, e.g. C60, or nanotubes, e.g.	16/0416	• • • • {comprising cells containing a single floating
	carbon or silicon nanotubes}		gate transistor and no select transistor, e.g.
13/04	• using optical elements {; using other beam accessed		UV EPROM}
	elements, e.g. electron or ion beam}	16/0425	{comprising cells containing a merged
13/041	• • {using photochromic storage elements		floating gate and select transistor}
	$(\underline{G11C \ 13/042} \ takes \ precedence)$	16/0433	• • • {comprising cells containing a single floating
13/042	• • {using information stored in the form of		gate transistor and one or more separate
	interference pattern}		select transistors}
13/043	• • • {using magnetic-optical storage elements}	16/0441	• • • {comprising cells containing multiple
13/044	• • • {using electro-optical elements}		floating gate devices, e.g. separate read-and-
13/045	{using photochromic storage elements}		write FAMOS transistors with connected
13/046	• • • {using other storage elements storing		floating gates}
	information in the form of an interference	16/045	• • • • {Floating gate memory cells with both P
	pattern}		and N channel memory transistors, usually
13/047	• • {using electro-optical elements (G11C 13/042		sharing a common floating gate}
10,01,	takes precedence)}	16/0458	{comprising two or more independent
13/048	• {using other optical storage elements}		floating gates which store independent
13/06	 using magneto-optical elements {(G11C 13/042) 		data}
13/00	takes precedence)}	16/0466	• • • {comprising cells with charge storage in an
	takes precedence);		insulating layer, e.g. metal-nitride-oxide-silicon
14/00	Digital stores characterised by arrangements		[MNOS], silicon-oxide-nitride-oxide-silicon
	of cells having volatile and non-volatile storage		[SONOS] (G11C 16/0483, G11C 16/0491 take
	properties for back-up when the power is down		precedence)}
14/0009	• {in which the volatile element is a DRAM cell}	16/0475	{comprising two or more independent
14/0018	• • {whereby the nonvolatile element is an EEPROM		storage sites which store independent data}
	element, e.g. a floating gate or metal-nitride-	16/0483	• • • {comprising cells having several storage
	oxide-silicon [MNOS] transistor}		transistors connected in series}
14/0027	• • {and the nonvolatile element is a ferroelectric	16/0491	{Virtual ground arrays}
	element}	16/06	Auxiliary circuits, e.g. for writing into memory
14/0036	• • {and the nonvolatile element is a magnetic RAM	16/08	Address circuits; Decoders; Word-line control
	[MRAM] element or ferromagnetic cell}	10/00	circuits
14/0045	• • {and the nonvolatile element is a resistive RAM	16/10	Programming or data input circuits
1 1/00 15	element, i.e. programmable resistors, e.g. formed	16/102	External programming circuits, e.g.
	of phase change or chalcogenide material}	10/102	EPROM programmers; In-circuit
14/0054	• {in which the volatile element is a SRAM cell}		programming or reprogramming; EPROM
14/0063	• {and the nonvolatile element is an EEPROM		emulators }
14/0003	element, e.g. a floating gate or MNOS transistor}	16/105	• • • • {Circuits or methods for updating contents
14/0072	• { and the nonvolatile element is a ferroelectric	10/103	of nonvolatile memory, especially with
14/0072	element}		'security' features to ensure reliable
1.4/0001	,		replacement, i.e. preventing that old data is
14/0081	{and the nonvolatile element is a magnetic RAM		lost before new data is reliably written}
1.4/000	[MRAM] element or ferromagnetic cell}	16/107	
14/009	• • {and the nonvolatile element is a resistive RAM	16/10/	• • • {Programming all cells in an array, sector or
	element, i.e. programmable resistors, e.g. formed	16/10	block to the same state prior to flash erasing}
	of phase change or chalcogenide material}	16/12	• • • Programming voltage switching circuits
15/00	Digital stores in which information comprising	16/14	Circuits for erasing electrically, e.g. erase
	one or more characteristic parts is written into		voltage switching circuits
	the store and in which information is read-out by	16/16	• • • for erasing blocks, e.g. arrays, words,
	searching for one or more of these characteristic		groups
	parts, i.e. associative or content-addressed stores	16/18	Circuits for erasing optically
15/02	using magnetic elements	16/20	Initialising; Data preset; Chip identification
15/04	 using semiconductor elements 	16/22	• • • Safety or protection circuits preventing
15/043	 using semiconductor elements • {using capacitive charge storage elements} 		unauthorised or accidental access to memory
15/046	. {using capacitive charge storage elements}. {using non-volatile storage elements}		cells
		16/225	• • • • {Preventing erasure, programming or reading
15/06	using cryogenic elements		when power supply voltages are outside the
16/00	Erasable programmable read-only memories		required ranges}
	(G11C 14/00 takes precedence)	16/24	Bit-line control circuits
16/02	electrically programmable	16/26	Sensing or reading circuits; Data output circuits
16/04	• using variable threshold transistors, e.g. FAMOS	16/28	using differential sensing or reference cells,
			e.g. dummy cells
		16/30	Power supply circuits
			· · · · · · · · · · · · · · · · · · ·

16/32	Timing circuits	16/3481	• • • • • {Circuits or methods to verify correct
16/34	Determination of programming status, e.g.		programming of nonvolatile memory
	threshold voltage, overprogramming or		cells whilst programming is in progress,
	underprogramming, retention		e.g. by detecting onset or cessation
16/3404	{Convergence or correction of memory cell		of current flow in cells and using
	threshold voltages; Repair or recovery of		the detector output to terminate
	overerased or overprogrammed cells}		programming}
16/3409	{Circuits or methods to recover overerased	16/3486	• • • • • {Circuits or methods to prevent
	nonvolatile memory cells detected during		overprogramming of nonvolatile
	erase verification, usually by means of a		memory cells, e.g. by detecting onset
	"soft" programming step}		or cessation of current flow in cells and
16/3413	{Circuits or methods to recover		using the detector output to terminate
	overprogrammed nonvolatile memory		programming}
	cells detected during program verification,	16/349	• • • {Arrangements for evaluating degradation,
	usually by means of a "soft" erasing step}		retention or wearout, e.g. by counting erase
16/3418	• • • {Disturbance prevention or evaluation;		cycles}
10,0.110	Refreshing of disturbed memory data}	16/3495	{Circuits or methods to detect or delay
16/3422	• • • • • Circuits or methods to evaluate read or		wearout of nonvolatile EPROM or
10/3422	write disturbance in nonvolatile memory,		EEPROM memory devices, e.g. by
	without steps to mitigate the problem}		counting numbers of erase or reprogram
16/3427	• • • • {Circuits or methods to prevent or reduce		cycles, by using multiple memory areas
10/3427	disturbance of the state of a memory		serially or cyclically}
	cell when neighbouring cells are read or		
	written }	17/00	Read-only memories programmable only once;
16/3431	,		Semi-permanent stores, e.g. manually-replaceable
10/3431	{Circuits or methods to detect disturbed nonvolatile memory cells, e.g. which still		information cards
	read as programmed but with threshold	17/005	• {with a storage element common to a large
	less than the program verify threshold or		number of data, e.g. perforated card (G11C 17/02,
	read as erased but with threshold greater		G11C 17/04 take precedence)}
	than the erase verify threshold, and to	17/02	• using magnetic or inductive elements (G11C 17/14
	reverse the disturbance via a refreshing		takes precedence)
	programming or erasing step}	17/04	• using capacitive elements (G11C 17/06,
16/3436	{Arrangements for verifying correct		G11C 17/14 take precedence)
10/3430	programming or erasure}	17/06	• using diode elements (G11C 17/14 takes
16/244			precedence)
16/344	{Arrangements for verifying correct	17/08	 using semiconductor devices, e.g. bipolar elements
16/2445	erasure or for detecting overerased cells}		(<u>G11C 17/06</u> , <u>G11C 17/14</u> take precedence)
16/3445	(Circuits or methods to verify correct	17/10	in which contents are determined during
16/045	erasure of nonvolatile memory cells}		manufacturing by a predetermined arrangement
16/345	{Circuits or methods to detect		of coupling elements, e.g. mask-programmable
	overerased nonvolatile memory cells,		ROM
16/2454	usually during erasure verification}	17/12	using field-effect devices
16/3454	{Arrangements for verifying correct	17/123	• • • {comprising cells having several storage
	programming or for detecting		transistors connected in series}
	overprogrammed cells}	17/126	{Virtual ground arrays}
16/3459	{Circuits or methods to verify correct	17/14	• in which contents are determined by selectively
	programming of nonvolatile memory		establishing, breaking or modifying connecting
- نستو	cells}		links by permanently altering the state of coupling
16/3463	{Circuits or methods to detect		elements, e.g. PROM
	overprogrammed nonvolatile memory	17/143	• • {using laser-fusible links}
	cells, usually during program	17/146	• • (Write once memory, i.e. allowing changing of
	verification}	17/140	memory content by writing additional bits}
16/3468	• • • • Prevention of overerasure or	17/16	 using electrically-fusible links
	overprogramming, e.g. by verifying whilst		-
	erasing or writing}	17/165	• • • {Memory cells which are electrically
16/3472	{Circuits or methods to verify correct		programmed to cause a change in resistance,
	erasure of nonvolatile memory cells		e.g. to permit multiple resistance steps to be
	whilst erasing is in progress, e.g. by		programmed rather than conduct to or from
	detecting onset or cessation of current		non-conduct change of fuses and antifuses
	flow in cells and using the detector		(digital stores using resistance random access
	output to terminate erasure}	15/10	memory elements <u>G11C 13/0002</u>)}
16/3477	• • • • • {Circuits or methods to prevent	17/18	Auxiliary circuits, e.g. for writing into memory
	overerasing of nonvolatile memory	19/00	Digital stores in which the information is moved
	cells, e.g. by detecting onset or cessation		stepwise, e.g. shift registers
	of current flow in cells and using the	19/005	• {with ferro-electric elements (condensers)}
	detector output to terminate erasing}	17/003	- (m retro electric elements (condensers))

19/02	 using magnetic elements (G11C 19/14 takes precedence) 	19/30	 using opto-electronic devices, i.e. light-emitting and photoelectric devices electrically- or optically-
19/04	using cores with one aperture or magnetic loop		coupled
19/06	 using structures with a number of apertures or 	19/32	using super-conductive elements
17/00	magnetic loops, e.g. transfluxors {laddic}	19/34	 using storage elements with more than two stable
19/08	 using thin films in plane structure 	17/54	states represented by steps, e.g. of voltage, current,
19/0808	-		phase, frequency
	• • { using magnetic domain propagation }	19/36	using {multistable} semiconductor elements
19/0816	• • • {using a rotating or alternating coplanar	19/38	 two-dimensional, e.g. horizontal and vertical shift
40,000	magnetic field}	19/30	
19/0825	• • • {using a variable perpendicular magnetic		registers
	field}	21/00	Digital stores in which the information circulates
19/0833	• • • {using magnetic domain interaction}		{continuously}(stepwise G11C 19/00)
19/0841	• • • { using electric current }	21/005	• {using electrical delay lines}
19/085	• • • {Generating magnetic fields therefor, e.g.	21/02	 using electromechanical delay lines, e.g. using a
	uniform magnetic field for magnetic domain	21/02	mercury tank
	stabilisation}	21/023	
19/0858	• • • {Generating, replicating or annihilating	21/023	tank}
	magnetic domains (also comprising different	21/026	,
	types of magnetic domains, e.g. "Hard	21/026	• • {using magnetostriction transducers, e.g. nickel
	Bubbles") (G11C 19/0866 takes precedence)}		delay line}
19/0866	{Detecting magnetic domains}	23/00	Digital stores characterised by movement of
19/0875	• • • (Organisation of a plurality of magnetic shift	20,00	mechanical parts to effect storage, e.g. using balls;
15/00/5	registers}		Storage elements therefor
19/0883	• • • {Means for switching magnetic domains		Storage elements therefor
17/0003	from one path into another path, i.e. transfer	25/00	Digital stores characterised by the use of flowing
	switches, swap gates or decoders}		media; Storage elements therefor
10/0001		25/00	
19/0891	• • • • {using hybrid structure, e.g. ion doped	27/00	Electric analogue stores, e.g. for storing
10/10	layers}		instantaneous values
19/10	• using thin films on rods; with twistors	27/005	• {with non-volatile charge storage, e.g. on floating
19/12	. using non-linear reactive devices in resonant circuits		gate or MNOS}
	{, e.g. parametrons; magnetic amplifiers with	27/02	• Sample-and-hold arrangements (G11C 27/04 takes
	overcritical feedback}		precedence)
19/14	 using magnetic elements in combination with active 	27/022	• {using a magnetic memory element}
	elements, e.g. discharge tubes, semiconductor	27/024	• • {using a capacitive memory element (G11C 27/04
	elements {(contains no documents, see provisionally		takes precedence)}
	<u>G11C 19/02</u> - <u>G11C 19/10</u>)}	27/026	• • • {associated with an amplifier (G11C 27/028
19/18	 using capacitors as main elements of the stages {(if 		takes precedence)}
	capacitors are used as auxiliary stage in between	27/028	• • • {Current mode circuits, e.g. switched current
	main stages with other elements, the latter take	277020	memories}
	precedence; G11C 19/005 takes precedence)	27/04	Shift registers
19/182	• • {in combination with semiconductor elements,	27/04	• Similar registers
	e.g. bipolar transistors, diodes}	29/00	Checking stores for correct operation {;
19/184	• • { with field-effect transistors, e.g. MOS-FET}		Subsequent repair}; Testing stores during standby
19/186	• • • {using only one transistor per capacitor, e.g.		or offline operation
19/100	bucket brigade shift register}	29/003	• {in serial memories}
10/100	{Organisation of a multiplicity of shift	29/006	• {at wafer scale level, i.e. wafer scale integration
19/188		25/000	[WSI]}
	registers, e.g. regeneration, timing or input-	29/02	 Detection or location of defective auxiliary circuits,
10/20	output circuits}	27/02	e.g. defective refresh counters
19/20	• using discharge tubes (G11C 19/14 takes	20/021	
	precedence)	29/021	• • {in voltage or current generators}
19/202	• • {with vacuum tubes (<u>G11C 19/207</u> takes	29/022	• • {in I/O circuitry}
	precedence)}	29/023	• • {in clock generator or timing circuitry}
19/205	• • {with gas-filled tubes (<u>G11C 19/207</u> takes	29/024	• • {in decoders}
	precedence)}	29/025	• • {in signal lines}
19/207	• • {with counting tubes}	29/026	• • {in sense amplifiers}
19/28	• using semiconductor elements (G11C 19/14,	29/027	• • {in fuses}
	G11C 19/36 take precedence)	29/028	• • {with adaption or trimming of parameters}
19/282	• { with charge storage in a depletion layer, i.e.	29/04	Detection or location of defective memory elements
•	charge coupled devices [CCD]}	27/07	{, e.g. cell constructio details, timing of test signals}
19/285	• • • {Peripheral circuits, e.g. for writing into the	2029/0401	• • {in embedded memories}
17/200	first stage; for reading-out of the last stage}		
19/287	• {Organisation of a multiplicity of shift registers}	2029/0403	• • {during or with feedback to manufacture}
17/401	• • (Organisation of a multiplicity of shift registers)	2029/0405	• • {comprising complete test loop}
		2029/0407	• • {on power on}
		2029/0409	• • {Online test}

2029/0411 • • {Online error correction}	29/50004 {of threshold voltage}
29/06 • • Acceleration testing	29/50008 • • • {of impedance}
29/08 • Functional testing, e.g. testing during refresh,	29/50012 {of timing}
power-on self testing [POST] or distributed	29/50016 {of retention}
testing	
29/10 Test algorithms, e.g. memory scan [MScan]	2029/5002 • • • {Characteristic}
algorithms; Test patterns, e.g. checkerboard	2029/5004 {Voltage}
patterns	2029/5006 {Current}
29/12 Built-in arrangements for testing, e.g. built-in	29/52 • Protection of memory contents; Detection of errors
self testing [BIST] {or interconnection details}	in memory contents
9 · · · · · · · · · · · · · · · · ·	29/54 • Arrangements for designing test circuits, e.g. design
29/12005 {comprising voltage or current generators}	for test [DFT] tools
29/1201 {comprising I/O circuitry}	29/56 • External testing equipment for static stores, e.g.
29/12015 {comprising clock generation or timing	automatic test equipment [ATE]; Interfaces therefor
circuitry}	29/56004 {Pattern generation}
2029/1202 {Word line control}	29/56008 • • {Error analysis, representation of errors}
2029/1204 • • • {Bit line control}	29/56012 {Timing aspects, clock generation,
2029/1206 • • • • {Location of test circuitry on chip or wafer}	synchronisation}
2029/1208 {Error catch memory}	29/56016 • • {Apparatus features}
29/14 Implementation of control logic, e.g. test	2029/5602 • • {Interface to device under test}
mode decoders	2029/5604 • • {Display of error information}
29/16 using microprogrammed units, e.g. state	
machines	,
29/18 Address generation devices; Devices	• {Masking faults in memories by using spares or by
for accessing memories, e.g. details of	reconfiguring}
addressing circuits	29/702 • • {by replacing auxiliary circuits, e.g. spare voltage
2029/1802 {Address decoder}	generators, decoders or sense amplifiers, to be
	used instead of defective ones}
,	29/72 • • { with optimized replacement algorithms }
2029/1806 {Address conversion or mapping, i.e.	29/74 {using duplex memories, i.e. using dual copies}
logical to physical address}	29/76 • • {using address translation or modifications}
29/20 using counters or linear-feedback shift	29/765 {in solid state disks}
registers [LFSR]	29/78 {using programmable devices}
29/22 Accessing serial memories	29/781 {combined in a redundant decoder}
29/24 Accessing extra cells, e.g. dummy cells or	29/783 • • • { with refresh of replacement cells, e.g. in
redundant cells	DRAMs}
29/26 Accessing multiple arrays (G11C 29/24)	29/785 {with redundancy programming schemes}
takes precedence)	29/787 {using a fuse hierarchy}
2029/2602 {Concurrent test}	29/789 { using a ruse increasery }
29/28 Dependent multiple arrays, e.g. multi-bit	· · ·
arrays	29/80 {with improved layout}
29/30 Accessing single arrays	29/802 {by encoding redundancy signals}
29/32 Serial access; Scan testing	29/804 {to prevent clustered faults}
2029/3202 {Scan chain}	29/806 {by reducing size of decoders}
29/34 Accessing multiple bits simultaneously	29/808 {using a flexible replacement scheme}
29/36 Data generation devices, e.g. data inverters	29/81 {using a hierarchical redundancy scheme}
	29/812 {using a reduced amount of fuses}
2029/3602 {Pattern generator}	29/814 {for optimized yield}
29/38 Response verification devices	29/816 {for an application-specific layout}
29/40 using compression techniques	29/818 {for dual-port memories}
2029/4002 {Comparison of products, i.e. test results	29/82 {for EEPROMs}
of chips or with golden chip}	
29/42 using error correcting codes [ECC] or	29/822 {for read only memories}
parity check	29/824 {for synchronous memories}
29/44 Indication or identification of errors, e.g. for	29/83 {with reduced power consumption}
repair	29/832 { with disconnection of faulty elements}
29/4401 {for self repair}	29/835 { with roll call arrangements for redundant
2029/4402 {Internal storage of test result, quality data,	substitutions}
chip identification, repair information}	29/838 • • • { with substitution of defective spares}
29/46 Test trigger logic	29/84 {with improved access time or stability}
29/48 Arrangements in static stores specially adapted	29/842 {by introducing a delay in a signal path}
for testing by means external to the store, e.g.	29/844 {by splitting the decoders in stages}
using direct memory access [DMA] or using	29/846 {by choosing redundant lines at an output
auxiliary access paths	stage}
29/50 • • Marginal testing, e.g. race, voltage or current	29/848 {by adjacent switching}
testing	

29/86	• • {in serial access memories, e.g. shift registers,	2211/406 Refreshing of dynamic cells
	CCDs, bubble memories}	2211/4061 Calibration or ate or cycle tuning
29/88	• • {with partially good memories}	2211/4062 Parity or ECC in refresh operations
29/883	• • • {using a single defective memory device with	2211/4063 Interleaved refresh operations
20/006	reduced capacity, e.g. half capacity}	2211/4065 Low level details of refresh operations
29/886	{combining plural defective memory devices	2211/4066 Pseudo-SRAMs
	to provide a contiguous address range, e.g. one device supplies working blocks to replace	2211/4067 Refresh in standby or low power modes
	defective blocks in another device}	2211/4068 Voltage or leakage in refresh operations
	defective blocks in another device;	2211/56 • Indexing scheme relating to G11C 11/56 and sub-
99/00	Subject matter not provided for in other groups of	groups for features not covered by these groups
	this subclass	2211/561 Multilevel memory cell aspects
2207/00	Indonina selecue veletina te amenanementa fen	2211/5611 Multilevel memory cell with more than one
2207/00	Indexing scheme relating to arrangements for writing information into, or reading information	control gate
	out from, a digital store	2211/5612 Multilevel memory cell with more than one
2207/002	Isolation gates, i.e. gates coupling bit lines to the	floating gate 2211/5613 Multilevel memory cell with additional gates,
2201/002	sense amplifier	2211/5613 Multilevel memory cell with additional gates, not being floating or control gates
2207/005	Transfer gates, i.e. gates coupling the sense	2211/5614 Multilevel memory cell comprising negative
	amplifier output to data lines, I/O lines or global bit	resistance, quantum tunneling or resonance
	lines	tunneling elements
2207/007	Register arrays	2211/5615 Multilevel magnetic memory cell using non-
2207/06	Sense amplifier related aspects	magnetic non-conducting interlayer, e.g. MTJ
2207/061	Sense amplifier enabled by a address transition	2211/5616 Multilevel magnetic memory cell using non-
	detection related control signal	magnetic conducting interlayer, e.g. GMR, SV,
2207/063	Current sense amplifiers	PSV
2207/065	Sense amplifier drivers	2211/5617 Multilevel ROM cell programmed by source,
2207/066	Frequency reading type sense amplifier	drain or gate contacting
2207/068	Integrator type sense amplifier	2211/562 Multilevel memory programming aspects
2207/10	Aspects relating to interfaces of memory device to	2211/5621 Multilevel programming verification
	external buses	2211/5622 Concurrent multilevel programming of more
2207/101	Analog or multilevel bus	than one cell
2207/102	Compression or decompression of data before	2211/5623 Concurrent multilevel programming and
	storage	reading
2207/104	Embedded memory devices, e.g. memories with	2211/5624 Concurrent multilevel programming and
	a processing device on the same die or ASIC	programming verification
	memory designs	2211/5625 Self-converging multilevel programming
2207/105	Aspects related to pads, pins or terminals	2211/563 Multilevel memory reading aspects
2207/107	Serial-parallel conversion of data or prefetch	2211/5631 Concurrent multilevel reading of more than one
2207/108	Wide data ports	cell
2207/12	Equalization of bit lines	2211/5632 Multilevel reading using successive
2207/16	Solid state audio	approximation
2207/22	Control and timing of internal memory operations	2211/5633 Mixed concurrent serial multilevel reading
2207/2209	Concurrent read and write	2211/5634 Reference cells
2207/2218	Late write	2211/564 . Miscellaneous aspects
2207/2227	Standby or low power modes	2211/5641 Multilevel memory having cells with different
2207/2236	Copy	number of storage levels Multilevel memory with huffare letches
2207/2245	Memory devices with an internal cache buffer	2211/5642 Multilevel memory with buffers, latches, registers at input or output
2207/2254	Calibration	
2207/2263	• Write conditionally, e.g. only if new data and old	2211/5643 Multilevel memory comprising cache storage devices
	data differ	2211/5644 Multilevel memory comprising counting
2207/2272	. Latency related aspects	devices
2207/2281	. Timing of a read operation	2211/5645 Multilevel memory with current-mirror
2207/229	Timing of a write operation	arrangements
2211/00	Indexing scheme relating to digital stores	2211/5646 Multilevel memory with flag bits, e.g. for
	characterized by the use of particular electric	showing that a "first page" of a word line is
	or magnetic storage elements; Storage elements	programmed but not a "second page"
	therefor	2211/5647 Multilevel memory with bit inversion
2211/401	Indexing scheme relating to cells needing refreshing	arrangement
	or charge regeneration, i.e. dynamic cells	2211/5648 Multilevel memory programming, reading
2211/4013	Memory devices with multiple cells per bit, e.g.	or erasing operations wherein the order or
	twin-cells	sequence of the operations is relevant
2211/4016	Memory devices with silicon-on-insulator cells	

2211/5649	Multilevel memory with plate line or layer, e.g.	2213/71 Three dimensional array
	in order to lower programming voltages	2213/72 . Array wherein the access device being a diode
2211/565	Multilevel memory comprising elements in	2213/73 . Array where access device function, e.g. diode
	triple well structure	function, being merged with memorizing function of memory element
2213/00	Indexing scheme relating to G11C 13/00 for	2213/74 . Array wherein each memory cell has more than
	features not covered by this group	one access device
2213/10	Resistive cells; Technology aspects	2213/75 . Array having a NAND structure comprising,
2213/11	Metal ion trapping, i.e. using memory material	for example, memory cells in series or memory
	including cavities, pores or spaces in form of	elements in series, a memory element being a
	tunnels or channels wherein metal ions can be	memory cell in parallel with an access transistor
	trapped but do not react and form an electro-	2213/76 . Array using an access device for each cell which
2212/12	deposit creating filaments or dendrites Non-metal ion trapping, i.e. using memory	being not a transistor and not a diode
2213/12	material trapping non-metal ions given by	2213/77 . Array wherein the memory element being directly
	the electrode or another layer during a write	connected to the bit lines and word lines without
	operation, e.g. trapping, doping	any access device being used
2213/13	Dissociation, i.e. using memory material	2213/78 . Array wherein the memory cells of a group share
2213/13	including molecules which, during a write	an access device, all the memory cells of the
	operation, are dissociated in ions which migrate	group having a common electrode and the access
	further in the memory material	device being not part of a word line or a bit line
2213/14	Use of different molecule structures as storage	driver
2218/11	states, e.g. part of molecule being rotated	2213/79 . Array wherein the access device being a transistor
2213/15	Current-voltage curve	2213/80 . Array wherein the substrate, the cell, the
2213/16	Memory cell being a nanotube, e.g. suspended	conductors and the access device are all made up
2213/10	nanotube	of organic materials
2213/17	Memory cell being a nanowire transistor	2213/81 . Array wherein the array conductors, e.g. word
2213/18	. Memory cell being a nanowire having RADIAL	lines, bit lines, are made of nanowires
2213/10	composition	2213/82 . Array having, for accessing a cell, a word line,
2213/19	Memory cell comprising at least a nanowire and	a bit line and a plate or source line receiving
2210/19	only two terminals	different potentials
2213/30	Resistive cell, memory material aspects	2216/00 Indexing scheme relating to G11C 16/00 and
2213/31	Material having complex metal oxide e g	
2213/31	Material having complex metal oxide, e.g. perovskite structure	subgroups, for features not directly covered by these groups
	perovskite structure	subgroups, for features not directly covered by
2213/31 2213/32		subgroups, for features not directly covered by these groups
	perovskite structure . Material having simple binary metal oxide structure	subgroups, for features not directly covered by these groups 2216/02 . Structural aspects of erasable programmable read-
2213/32	perovskite structure . Material having simple binary metal oxide structure . Material including silicon	 subgroups, for features not directly covered by these groups 2216/02 • Structural aspects of erasable programmable readonly memories 2216/04 • Nonvolatile memory cell provided with a separate control gate for erasing the cells, i.e. erase gate,
2213/32 2213/33	 perovskite structure Material having simple binary metal oxide structure Material including silicon Material includes an oxide or a nitride 	subgroups, for features not directly covered by these groups 2216/02 • Structural aspects of erasable programmable readonly memories 2216/04 • Nonvolatile memory cell provided with a separate control gate for erasing the cells, i.e. erase gate, independent of the normal read control gate
2213/32 2213/33 2213/34	perovskite structure . Material having simple binary metal oxide structure . Material including silicon . Material includes an oxide or a nitride . Material including carbon, e.g. graphite,	subgroups, for features not directly covered by these groups 2216/02 • Structural aspects of erasable programmable readonly memories 2216/04 • Nonvolatile memory cell provided with a separate control gate for erasing the cells, i.e. erase gate, independent of the normal read control gate 2216/06 • Floating gate cells in which the floating gate
2213/32 2213/33 2213/34	perovskite structure . Material having simple binary metal oxide structure . Material including silicon . Material includes an oxide or a nitride . Material including carbon, e.g. graphite, grapheme	subgroups, for features not directly covered by these groups 2216/02 • Structural aspects of erasable programmable readonly memories 2216/04 • Nonvolatile memory cell provided with a separate control gate for erasing the cells, i.e. erase gate, independent of the normal read control gate 2216/06 • Floating gate cells in which the floating gate consists of multiple isolated silicon islands, e.g.
2213/32 2213/33 2213/34 2213/35 2213/50	perovskite structure . Material having simple binary metal oxide structure . Material including silicon . Material includes an oxide or a nitride . Material including carbon, e.g. graphite, grapheme . Resistive cell structure aspects	subgroups, for features not directly covered by these groups 2216/02 • Structural aspects of erasable programmable readonly memories 2216/04 • Nonvolatile memory cell provided with a separate control gate for erasing the cells, i.e. erase gate, independent of the normal read control gate 2216/06 • Floating gate cells in which the floating gate consists of multiple isolated silicon islands, e.g. nanocrystals
2213/32 2213/33 2213/34 2213/35	perovskite structure . Material having simple binary metal oxide structure . Material including silicon . Material includes an oxide or a nitride . Material including carbon, e.g. graphite, grapheme . Resistive cell structure aspects . Structure including a barrier layer preventing or	subgroups, for features not directly covered by these groups 2216/02 • Structural aspects of erasable programmable readonly memories 2216/04 • Nonvolatile memory cell provided with a separate control gate for erasing the cells, i.e. erase gate, independent of the normal read control gate 2216/06 • Floating gate cells in which the floating gate consists of multiple isolated silicon islands, e.g. nanocrystals 2216/08 • Nonvolatile memory wherein data storage is
2213/32 2213/33 2213/34 2213/35 2213/50	perovskite structure . Material having simple binary metal oxide structure . Material including silicon . Material includes an oxide or a nitride . Material including carbon, e.g. graphite, grapheme . Resistive cell structure aspects	subgroups, for features not directly covered by these groups 2216/02 • Structural aspects of erasable programmable readonly memories 2216/04 • Nonvolatile memory cell provided with a separate control gate for erasing the cells, i.e. erase gate, independent of the normal read control gate 2216/06 • Floating gate cells in which the floating gate consists of multiple isolated silicon islands, e.g. nanocrystals 2216/08 • Nonvolatile memory wherein data storage is accomplished by storing relatively few electrons
2213/32 2213/33 2213/34 2213/35 2213/50	perovskite structure . Material having simple binary metal oxide structure . Material including silicon . Material includes an oxide or a nitride . Material including carbon, e.g. graphite, grapheme . Resistive cell structure aspects . Structure including a barrier layer preventing or limiting migration, diffusion of ions or charges or	subgroups, for features not directly covered by these groups 2216/02 • Structural aspects of erasable programmable readonly memories 2216/04 • Nonvolatile memory cell provided with a separate control gate for erasing the cells, i.e. erase gate, independent of the normal read control gate 2216/06 • Floating gate cells in which the floating gate consists of multiple isolated silicon islands, e.g. nanocrystals 2216/08 • Nonvolatile memory wherein data storage is accomplished by storing relatively few electrons in the storage layer, i.e. single electron memory
2213/32 2213/33 2213/34 2213/35 2213/50 2213/51	perovskite structure . Material having simple binary metal oxide structure . Material including silicon . Material includes an oxide or a nitride . Material including carbon, e.g. graphite, grapheme . Resistive cell structure aspects . Structure including a barrier layer preventing or limiting migration, diffusion of ions or charges or formation of electrolytes near an electrode	subgroups, for features not directly covered by these groups 2216/02 • Structural aspects of erasable programmable readonly memories 2216/04 • Nonvolatile memory cell provided with a separate control gate for erasing the cells, i.e. erase gate, independent of the normal read control gate 2216/06 • Floating gate cells in which the floating gate consists of multiple isolated silicon islands, e.g. nanocrystals 2216/08 • Nonvolatile memory wherein data storage is accomplished by storing relatively few electrons in the storage layer, i.e. single electron memory 2216/10 • Floating gate memory cells with a single
2213/32 2213/33 2213/34 2213/35 2213/50 2213/51	perovskite structure . Material having simple binary metal oxide structure . Material including silicon . Material includes an oxide or a nitride . Material including carbon, e.g. graphite, grapheme . Resistive cell structure aspects . Structure including a barrier layer preventing or limiting migration, diffusion of ions or charges or formation of electrolytes near an electrode . Structure characterized by the electrode material,	subgroups, for features not directly covered by these groups 2216/02 • Structural aspects of erasable programmable readonly memories 2216/04 • Nonvolatile memory cell provided with a separate control gate for erasing the cells, i.e. erase gate, independent of the normal read control gate 2216/06 • Floating gate cells in which the floating gate consists of multiple isolated silicon islands, e.g. nanocrystals 2216/08 • Nonvolatile memory wherein data storage is accomplished by storing relatively few electrons in the storage layer, i.e. single electron memory 2216/10 • Floating gate memory cells with a single polysilicon layer
2213/32 2213/33 2213/34 2213/35 2213/50 2213/51 2213/52	perovskite structure . Material having simple binary metal oxide structure . Material including silicon . Material includes an oxide or a nitride . Material including carbon, e.g. graphite, grapheme . Resistive cell structure aspects . Structure including a barrier layer preventing or limiting migration, diffusion of ions or charges or formation of electrolytes near an electrode . Structure characterized by the electrode material, shape, etc.	subgroups, for features not directly covered by these groups 2216/02 • Structural aspects of erasable programmable readonly memories 2216/04 • Nonvolatile memory cell provided with a separate control gate for erasing the cells, i.e. erase gate, independent of the normal read control gate 2216/06 • Floating gate cells in which the floating gate consists of multiple isolated silicon islands, e.g. nanocrystals 2216/08 • Nonvolatile memory wherein data storage is accomplished by storing relatively few electrons in the storage layer, i.e. single electron memory 2216/10 • Floating gate memory cells with a single polysilicon layer 2216/12 • Reading and writing aspects of erasable
2213/32 2213/33 2213/34 2213/35 2213/50 2213/51 2213/52	perovskite structure . Material having simple binary metal oxide structure . Material including silicon . Material includes an oxide or a nitride . Material including carbon, e.g. graphite, grapheme . Resistive cell structure aspects . Structure including a barrier layer preventing or limiting migration, diffusion of ions or charges or formation of electrolytes near an electrode . Structure characterized by the electrode material, shape, etc. . Structure wherein the resistive material being in a	subgroups, for features not directly covered by these groups 2216/02 • Structural aspects of erasable programmable readonly memories 2216/04 • Nonvolatile memory cell provided with a separate control gate for erasing the cells, i.e. erase gate, independent of the normal read control gate 2216/06 • Floating gate cells in which the floating gate consists of multiple isolated silicon islands, e.g. nanocrystals 2216/08 • Nonvolatile memory wherein data storage is accomplished by storing relatively few electrons in the storage layer, i.e. single electron memory 2216/10 • Floating gate memory cells with a single polysilicon layer 2216/12 • Reading and writing aspects of erasable programmable read-only memories
2213/32 2213/33 2213/34 2213/35 2213/50 2213/51 2213/52 2213/53	 perovskite structure Material having simple binary metal oxide structure Material including silicon Material includes an oxide or a nitride Material including carbon, e.g. graphite, grapheme Resistive cell structure aspects Structure including a barrier layer preventing or limiting migration, diffusion of ions or charges or formation of electrolytes near an electrode Structure characterized by the electrode material, shape, etc. Structure wherein the resistive material being in a transistor, e.g. gate 	subgroups, for features not directly covered by these groups 2216/02 • Structural aspects of erasable programmable readonly memories 2216/04 • Nonvolatile memory cell provided with a separate control gate for erasing the cells, i.e. erase gate, independent of the normal read control gate 2216/06 • Floating gate cells in which the floating gate consists of multiple isolated silicon islands, e.g. nanocrystals 2216/08 • Nonvolatile memory wherein data storage is accomplished by storing relatively few electrons in the storage layer, i.e. single electron memory 2216/10 • Floating gate memory cells with a single polysilicon layer 2216/12 • Reading and writing aspects of erasable programmable read-only memories 2216/14 • Circuits or methods to write a page or sector of
2213/32 2213/33 2213/34 2213/35 2213/50 2213/51 2213/52 2213/53	 perovskite structure Material having simple binary metal oxide structure Material including silicon Material includes an oxide or a nitride Material including carbon, e.g. graphite, grapheme Resistive cell structure aspects Structure including a barrier layer preventing or limiting migration, diffusion of ions or charges or formation of electrolytes near an electrode Structure characterized by the electrode material, shape, etc. Structure wherein the resistive material being in a transistor, e.g. gate Structure including a tunneling barrier layer, 	subgroups, for features not directly covered by these groups 2216/02 • Structural aspects of erasable programmable readonly memories 2216/04 • Nonvolatile memory cell provided with a separate control gate for erasing the cells, i.e. erase gate, independent of the normal read control gate 2216/06 • Floating gate cells in which the floating gate consists of multiple isolated silicon islands, e.g. nanocrystals 2216/08 • Nonvolatile memory wherein data storage is accomplished by storing relatively few electrons in the storage layer, i.e. single electron memory 2216/10 • Floating gate memory cells with a single polysilicon layer 2216/12 • Reading and writing aspects of erasable programmable read-only memories 2216/14 • Circuits or methods to write a page or sector of information simultaneously into a nonvolatile
2213/32 2213/33 2213/34 2213/35 2213/50 2213/51 2213/52 2213/53	 Material having simple binary metal oxide structure Material including silicon Material includes an oxide or a nitride Material including carbon, e.g. graphite, grapheme Resistive cell structure aspects Structure including a barrier layer preventing or limiting migration, diffusion of ions or charges or formation of electrolytes near an electrode Structure characterized by the electrode material, shape, etc. Structure wherein the resistive material being in a transistor, e.g. gate Structure including a tunneling barrier layer, the memory effect implying the modification of tunnel barrier conductivity Structure including two electrodes, a memory 	subgroups, for features not directly covered by these groups 2216/02 • Structural aspects of erasable programmable readonly memories 2216/04 • Nonvolatile memory cell provided with a separate control gate for erasing the cells, i.e. erase gate, independent of the normal read control gate 2216/06 • Floating gate cells in which the floating gate consists of multiple isolated silicon islands, e.g. nanocrystals 2216/08 • Nonvolatile memory wherein data storage is accomplished by storing relatively few electrons in the storage layer, i.e. single electron memory 2216/10 • Floating gate memory cells with a single polysilicon layer 2216/12 • Reading and writing aspects of erasable programmable read-only memories 2216/14 • Circuits or methods to write a page or sector of information simultaneously into a nonvolatile memory, typically a complete row or word line in
2213/32 2213/33 2213/34 2213/35 2213/50 2213/51 2213/52 2213/53 2213/54	 Material having simple binary metal oxide structure Material including silicon Material includes an oxide or a nitride Material including carbon, e.g. graphite, grapheme Resistive cell structure aspects Structure including a barrier layer preventing or limiting migration, diffusion of ions or charges or formation of electrolytes near an electrode Structure characterized by the electrode material, shape, etc. Structure wherein the resistive material being in a transistor, e.g. gate Structure including a tunneling barrier layer, the memory effect implying the modification of tunnel barrier conductivity Structure including two electrodes, a memory active layer and at least two other layers which 	subgroups, for features not directly covered by these groups 2216/02 • Structural aspects of erasable programmable readonly memories 2216/04 • Nonvolatile memory cell provided with a separate control gate for erasing the cells, i.e. erase gate, independent of the normal read control gate 2216/06 • Floating gate cells in which the floating gate consists of multiple isolated silicon islands, e.g. nanocrystals 2216/08 • Nonvolatile memory wherein data storage is accomplished by storing relatively few electrons in the storage layer, i.e. single electron memory 2216/10 • Floating gate memory cells with a single polysilicon layer 2216/12 • Reading and writing aspects of erasable programmable read-only memories 2216/14 • Circuits or methods to write a page or sector of information simultaneously into a nonvolatile memory, typically a complete row or word line in flash memory
2213/32 2213/33 2213/34 2213/35 2213/50 2213/51 2213/52 2213/53 2213/54	 Material having simple binary metal oxide structure Material including silicon Material includes an oxide or a nitride Material including carbon, e.g. graphite, grapheme Resistive cell structure aspects Structure including a barrier layer preventing or limiting migration, diffusion of ions or charges or formation of electrolytes near an electrode Structure characterized by the electrode material, shape, etc. Structure wherein the resistive material being in a transistor, e.g. gate Structure including a tunneling barrier layer, the memory effect implying the modification of tunnel barrier conductivity Structure including two electrodes, a memory active layer and at least two other layers which can be a passive or source or reservoir layer or a 	subgroups, for features not directly covered by these groups 2216/02 • Structural aspects of erasable programmable readonly memories 2216/04 • Nonvolatile memory cell provided with a separate control gate for erasing the cells, i.e. erase gate, independent of the normal read control gate 2216/06 • Floating gate cells in which the floating gate consists of multiple isolated silicon islands, e.g. nanocrystals 2216/08 • Nonvolatile memory wherein data storage is accomplished by storing relatively few electrons in the storage layer, i.e. single electron memory 2216/10 • Floating gate memory cells with a single polysilicon layer 2216/12 • Reading and writing aspects of erasable programmable read-only memories 2216/14 • Circuits or methods to write a page or sector of information simultaneously into a nonvolatile memory, typically a complete row or word line in flash memory 2216/16 • Flash programming of all the cells in an array,
2213/32 2213/33 2213/34 2213/35 2213/50 2213/51 2213/52 2213/53 2213/54 2213/55	 Material having simple binary metal oxide structure Material including silicon Material includes an oxide or a nitride Material including carbon, e.g. graphite, grapheme Resistive cell structure aspects Structure including a barrier layer preventing or limiting migration, diffusion of ions or charges or formation of electrolytes near an electrode Structure characterized by the electrode material, shape, etc. Structure wherein the resistive material being in a transistor, e.g. gate Structure including a tunneling barrier layer, the memory effect implying the modification of tunnel barrier conductivity Structure including two electrodes, a memory active layer and at least two other layers which can be a passive or source or reservoir layer or a less doped memory active layer 	subgroups, for features not directly covered by these groups 2216/02 • Structural aspects of erasable programmable readonly memories 2216/04 • Nonvolatile memory cell provided with a separate control gate for erasing the cells, i.e. erase gate, independent of the normal read control gate 2216/06 • Floating gate cells in which the floating gate consists of multiple isolated silicon islands, e.g. nanocrystals 2216/08 • Nonvolatile memory wherein data storage is accomplished by storing relatively few electrons in the storage layer, i.e. single electron memory 2216/10 • Floating gate memory cells with a single polysilicon layer 2216/12 • Reading and writing aspects of erasable programmable read-only memories 2216/14 • Circuits or methods to write a page or sector of information simultaneously into a nonvolatile memory, typically a complete row or word line in flash memory 2216/16 • Flash programming of all the cells in an array, sector or block simultaneously
2213/32 2213/33 2213/34 2213/35 2213/50 2213/51 2213/52 2213/53 2213/54	 Material having simple binary metal oxide structure Material including silicon Material includes an oxide or a nitride Material including carbon, e.g. graphite, grapheme Resistive cell structure aspects Structure including a barrier layer preventing or limiting migration, diffusion of ions or charges or formation of electrolytes near an electrode Structure characterized by the electrode material, shape, etc. Structure wherein the resistive material being in a transistor, e.g. gate Structure including a tunneling barrier layer, the memory effect implying the modification of tunnel barrier conductivity Structure including two electrodes, a memory active layer and at least two other layers which can be a passive or source or reservoir layer or a less doped memory active layer Structure including two electrodes, a memory 	subgroups, for features not directly covered by these groups 2216/02 • Structural aspects of erasable programmable readonly memories 2216/04 • Nonvolatile memory cell provided with a separate control gate for erasing the cells, i.e. erase gate, independent of the normal read control gate 2216/06 • Floating gate cells in which the floating gate consists of multiple isolated silicon islands, e.g. nanocrystals 2216/08 • Nonvolatile memory wherein data storage is accomplished by storing relatively few electrons in the storage layer, i.e. single electron memory 2216/10 • Floating gate memory cells with a single polysilicon layer 2216/12 • Reading and writing aspects of erasable programmable read-only memories 2216/14 • Circuits or methods to write a page or sector of information simultaneously into a nonvolatile memory, typically a complete row or word line in flash memory 2216/16 • Flash programming of all the cells in an array, sector or block simultaneously • Flash erasure of all the cells in an array, sector or
2213/32 2213/33 2213/34 2213/35 2213/50 2213/51 2213/52 2213/53 2213/54 2213/55	 Material having simple binary metal oxide structure Material including silicon Material includes an oxide or a nitride Material including carbon, e.g. graphite, grapheme Resistive cell structure aspects Structure including a barrier layer preventing or limiting migration, diffusion of ions or charges or formation of electrolytes near an electrode Structure characterized by the electrode material, shape, etc. Structure wherein the resistive material being in a transistor, e.g. gate Structure including a tunneling barrier layer, the memory effect implying the modification of tunnel barrier conductivity Structure including two electrodes, a memory active layer and at least two other layers which can be a passive or source or reservoir layer or a less doped memory active layer Structure including two electrodes, a memory active layer and a so called passive or source 	subgroups, for features not directly covered by these groups 2216/02 • Structural aspects of erasable programmable readonly memories 2216/04 • Nonvolatile memory cell provided with a separate control gate for erasing the cells, i.e. erase gate, independent of the normal read control gate 2216/06 • Floating gate cells in which the floating gate consists of multiple isolated silicon islands, e.g. nanocrystals 2216/08 • Nonvolatile memory wherein data storage is accomplished by storing relatively few electrons in the storage layer, i.e. single electron memory 2216/10 • Floating gate memory cells with a single polysilicon layer 2216/12 • Reading and writing aspects of erasable programmable read-only memories 2216/14 • Circuits or methods to write a page or sector of information simultaneously into a nonvolatile memory, typically a complete row or word line in flash memory 2216/16 • Flash programming of all the cells in an array, sector or block simultaneously 2216/18 • Flash erasure of all the cells in an array, sector or block simultaneously
2213/32 2213/33 2213/34 2213/35 2213/50 2213/51 2213/52 2213/53 2213/54 2213/55	 Material having simple binary metal oxide structure Material including silicon Material includes an oxide or a nitride Material including carbon, e.g. graphite, grapheme Resistive cell structure aspects Structure including a barrier layer preventing or limiting migration, diffusion of ions or charges or formation of electrolytes near an electrode Structure characterized by the electrode material, shape, etc. Structure wherein the resistive material being in a transistor, e.g. gate Structure including a tunneling barrier layer, the memory effect implying the modification of tunnel barrier conductivity Structure including two electrodes, a memory active layer and at least two other layers which can be a passive or source or reservoir layer or a less doped memory active layer Structure including two electrodes, a memory active layer and a so called passive or source or reservoir layer which is NOT an electrode, 	subgroups, for features not directly covered by these groups 2216/02 • Structural aspects of erasable programmable readonly memories 2216/04 • Nonvolatile memory cell provided with a separate control gate for erasing the cells, i.e. erase gate, independent of the normal read control gate 2216/06 • Floating gate cells in which the floating gate consists of multiple isolated silicon islands, e.g. nanocrystals 2216/08 • Nonvolatile memory wherein data storage is accomplished by storing relatively few electrons in the storage layer, i.e. single electron memory 2216/10 • Floating gate memory cells with a single polysilicon layer 2216/12 • Reading and writing aspects of erasable programmable read-only memories 2216/14 • Circuits or methods to write a page or sector of information simultaneously into a nonvolatile memory, typically a complete row or word line in flash memory 2216/16 • Flash programming of all the cells in an array, sector or block simultaneously 2216/20 • Suspension of programming or erasing cells in an
2213/32 2213/33 2213/34 2213/35 2213/50 2213/51 2213/52 2213/53 2213/54 2213/55	 Material having simple binary metal oxide structure Material including silicon Material includes an oxide or a nitride Material including carbon, e.g. graphite, grapheme Resistive cell structure aspects Structure including a barrier layer preventing or limiting migration, diffusion of ions or charges or formation of electrolytes near an electrode Structure characterized by the electrode material, shape, etc. Structure wherein the resistive material being in a transistor, e.g. gate Structure including a tunneling barrier layer, the memory effect implying the modification of tunnel barrier conductivity Structure including two electrodes, a memory active layer and at least two other layers which can be a passive or source or reservoir layer or a less doped memory active layer Structure including two electrodes, a memory active layer and a so called passive or source or reservoir layer which is NOT an electrode, wherein the passive or source or reservoir layer is 	subgroups, for features not directly covered by these groups 2216/02 • Structural aspects of erasable programmable readonly memories 2216/04 • Nonvolatile memory cell provided with a separate control gate for erasing the cells, i.e. erase gate, independent of the normal read control gate 2216/06 • Floating gate cells in which the floating gate consists of multiple isolated silicon islands, e.g. nanocrystals 2216/08 • Nonvolatile memory wherein data storage is accomplished by storing relatively few electrons in the storage layer, i.e. single electron memory 2216/10 • Floating gate memory cells with a single polysilicon layer 2216/12 • Reading and writing aspects of erasable programmable read-only memories 2216/14 • Circuits or methods to write a page or sector of information simultaneously into a nonvolatile memory, typically a complete row or word line in flash memory 2216/16 • Flash programming of all the cells in an array, sector or block simultaneously 2216/20 • Suspension of programming or erasing cells in an array in order to read other cells in it
2213/32 2213/33 2213/34 2213/35 2213/50 2213/51 2213/52 2213/53 2213/54 2213/55	 Material having simple binary metal oxide structure Material including silicon Material includes an oxide or a nitride Material including carbon, e.g. graphite, grapheme Resistive cell structure aspects Structure including a barrier layer preventing or limiting migration, diffusion of ions or charges or formation of electrolytes near an electrode Structure characterized by the electrode material, shape, etc. Structure wherein the resistive material being in a transistor, e.g. gate Structure including a tunneling barrier layer, the memory effect implying the modification of tunnel barrier conductivity Structure including two electrodes, a memory active layer and at least two other layers which can be a passive or source or reservoir layer or a less doped memory active layer Structure including two electrodes, a memory active layer and a so called passive or source or reservoir layer which is NOT an electrode, wherein the passive or source or reservoir layer is a source of ions which migrate afterwards in the 	subgroups, for features not directly covered by these groups 2216/02 • Structural aspects of erasable programmable readonly memories 2216/04 • Nonvolatile memory cell provided with a separate control gate for erasing the cells, i.e. erase gate, independent of the normal read control gate 2216/06 • Floating gate cells in which the floating gate consists of multiple isolated silicon islands, e.g. nanocrystals 2216/08 • Nonvolatile memory wherein data storage is accomplished by storing relatively few electrons in the storage layer, i.e. single electron memory 2216/10 • Floating gate memory cells with a single polysilicon layer 2216/12 • Reading and writing aspects of erasable programmable read-only memories 2216/14 • Circuits or methods to write a page or sector of information simultaneously into a nonvolatile memory, typically a complete row or word line in flash memory 2216/16 • Flash programming of all the cells in an array, sector or block simultaneously 2216/18 • Flash erasure of all the cells in an array, sector or block simultaneously 2216/20 • Suspension of programming or erasing cells in an array in order to read other cells in it
2213/32 2213/33 2213/34 2213/35 2213/50 2213/51 2213/52 2213/53 2213/54 2213/55	 Material having simple binary metal oxide structure Material including silicon Material includes an oxide or a nitride Material including carbon, e.g. graphite, grapheme Resistive cell structure aspects Structure including a barrier layer preventing or limiting migration, diffusion of ions or charges or formation of electrolytes near an electrode Structure characterized by the electrode material, shape, etc. Structure wherein the resistive material being in a transistor, e.g. gate Structure including a tunneling barrier layer, the memory effect implying the modification of tunnel barrier conductivity Structure including two electrodes, a memory active layer and at least two other layers which can be a passive or source or reservoir layer or a less doped memory active layer Structure including two electrodes, a memory active layer and a so called passive or source or reservoir layer which is NOT an electrode, wherein the passive or source or reservoir layer is a source of ions which migrate afterwards in the memory active layer to be only trapped there, to 	subgroups, for features not directly covered by these groups 2216/02 • Structural aspects of erasable programmable readonly memories 2216/04 • Nonvolatile memory cell provided with a separate control gate for erasing the cells, i.e. erase gate, independent of the normal read control gate 2216/06 • Floating gate cells in which the floating gate consists of multiple isolated silicon islands, e.g. nanocrystals 2216/08 • Nonvolatile memory wherein data storage is accomplished by storing relatively few electrons in the storage layer, i.e. single electron memory 2216/10 • Floating gate memory cells with a single polysilicon layer 2216/12 • Reading and writing aspects of erasable programmable read-only memories 2216/14 • Circuits or methods to write a page or sector of information simultaneously into a nonvolatile memory, typically a complete row or word line in flash memory 2216/16 • Flash programming of all the cells in an array, sector or block simultaneously 2216/20 • Suspension of programming or erasing cells in an array in order to read other cells in it 2216/22 • Nonvolatile memory in which reading can be carried out from one memory bank or array whilst
2213/32 2213/33 2213/34 2213/35 2213/50 2213/51 2213/52 2213/53 2213/54 2213/55	 Material having simple binary metal oxide structure Material including silicon Material includes an oxide or a nitride Material including carbon, e.g. graphite, grapheme Resistive cell structure aspects Structure including a barrier layer preventing or limiting migration, diffusion of ions or charges or formation of electrolytes near an electrode Structure characterized by the electrode material, shape, etc. Structure wherein the resistive material being in a transistor, e.g. gate Structure including a tunneling barrier layer, the memory effect implying the modification of tunnel barrier conductivity Structure including two electrodes, a memory active layer and at least two other layers which can be a passive or source or reservoir layer or a less doped memory active layer Structure including two electrodes, a memory active layer and a so called passive or source or reservoir layer which is NOT an electrode, wherein the passive or source or reservoir layer is a source of ions which migrate afterwards in the memory active layer to be only trapped there, to form conductive filaments there or to react with 	subgroups, for features not directly covered by these groups 2216/02 • Structural aspects of erasable programmable readonly memories 2216/04 • Nonvolatile memory cell provided with a separate control gate for erasing the cells, i.e. erase gate, independent of the normal read control gate 2216/06 • Floating gate cells in which the floating gate consists of multiple isolated silicon islands, e.g. nanocrystals 2216/08 • Nonvolatile memory wherein data storage is accomplished by storing relatively few electrons in the storage layer, i.e. single electron memory 2216/10 • Floating gate memory cells with a single polysilicon layer 2216/12 • Reading and writing aspects of erasable programmable read-only memories 2216/14 • Circuits or methods to write a page or sector of information simultaneously into a nonvolatile memory, typically a complete row or word line in flash memory 2216/16 • Flash programming of all the cells in an array, sector or block simultaneously 2216/20 • Suspension of programming or erasing cells in an array in order to read other cells in it 2216/22 • Nonvolatile memory in which reading can be carried out from one memory bank or array whilst a word or sector in another bank or array is being
2213/32 2213/33 2213/34 2213/35 2213/50 2213/51 2213/52 2213/53 2213/54 2213/55	 Material having simple binary metal oxide structure Material including silicon Material includes an oxide or a nitride Material including carbon, e.g. graphite, grapheme Resistive cell structure aspects Structure including a barrier layer preventing or limiting migration, diffusion of ions or charges or formation of electrolytes near an electrode Structure characterized by the electrode material, shape, etc. Structure wherein the resistive material being in a transistor, e.g. gate Structure including a tunneling barrier layer, the memory effect implying the modification of tunnel barrier conductivity Structure including two electrodes, a memory active layer and at least two other layers which can be a passive or source or reservoir layer or a less doped memory active layer Structure including two electrodes, a memory active layer and a so called passive or source or reservoir layer which is NOT an electrode, wherein the passive or source or reservoir layer is a source of ions which migrate afterwards in the memory active layer to be only trapped there, to 	subgroups, for features not directly covered by these groups 2216/02 • Structural aspects of erasable programmable readonly memories 2216/04 • Nonvolatile memory cell provided with a separate control gate for erasing the cells, i.e. erase gate, independent of the normal read control gate 2216/06 • Floating gate cells in which the floating gate consists of multiple isolated silicon islands, e.g. nanocrystals 2216/08 • Nonvolatile memory wherein data storage is accomplished by storing relatively few electrons in the storage layer, i.e. single electron memory 2216/10 • Floating gate memory cells with a single polysilicon layer 2216/12 • Reading and writing aspects of erasable programmable read-only memories 2216/14 • Circuits or methods to write a page or sector of information simultaneously into a nonvolatile memory, typically a complete row or word line in flash memory 2216/16 • Flash programming of all the cells in an array, sector or block simultaneously 2216/20 • Suspension of programming or erasing cells in an array in order to read other cells in it 2216/22 • Nonvolatile memory in which reading can be carried out from one memory bank or array whilst

2213/70 • Resistive array aspects

2216/24	• Nonvolatile memory in which programming can be carried out in one memory bank or array whilst a word or sector in another bank or array is being erased simultaneously
2216/26	Floating gate memory which is adapted to be one-time programmable [OTP], e.g. containing multiple OTP blocks permitting limited update ability
2216/28	• Floating gate memory programmed by reverse programming, e.g. programmed with negative gate voltage and erased with positive gate voltage or programmed with high source or drain voltage and erased with high gate voltage
2216/30	Reduction of number of input/output pins by using a serial interface to transmit or receive addresses or data, i.e. serial access memory
2229/00	Indering asheme veleting to sheeking stones for
2229/00	Indexing scheme relating to checking stores for
2229/00	correct operation, subsequent repair or testing
2229/00	
2229/00	correct operation, subsequent repair or testing
	correct operation, subsequent repair or testing stores during standby or offline operation
	correct operation, subsequent repair or testing stores during standby or offline operation Indexing scheme relating to G11C 29/70, for
2229/70	 correct operation, subsequent repair or testing stores during standby or offline operation Indexing scheme relating to G11C 29/70, for implementation aspects of redundancy repair
2229/70	 correct operation, subsequent repair or testing stores during standby or offline operation Indexing scheme relating to G11C 29/70, for implementation aspects of redundancy repair Location of redundancy information
2229/70	 correct operation, subsequent repair or testing stores during standby or offline operation Indexing scheme relating to G11C 29/70, for implementation aspects of redundancy repair Location of redundancy information Redundancy information stored in a part of the
2229/70 2229/72 2229/723	 correct operation, subsequent repair or testing stores during standby or offline operation Indexing scheme relating to G11C 29/70, for implementation aspects of redundancy repair Location of redundancy information Redundancy information stored in a part of the memory core to be repaired
2229/70 2229/72 2229/723	 correct operation, subsequent repair or testing stores during standby or offline operation Indexing scheme relating to G11C 29/70, for implementation aspects of redundancy repair Location of redundancy information Redundancy information stored in a part of the memory core to be repaired Redundancy information loaded from the
2229/70 2229/72 2229/723 2229/726	 correct operation, subsequent repair or testing stores during standby or offline operation Indexing scheme relating to G11C 29/70, for implementation aspects of redundancy repair Location of redundancy information Redundancy information stored in a part of the memory core to be repaired Redundancy information loaded from the outside into the memory
2229/70 2229/72 2229/723 2229/726 2229/74	 correct operation, subsequent repair or testing stores during standby or offline operation Indexing scheme relating to G11C 29/70, for implementation aspects of redundancy repair Location of redundancy information Redundancy information stored in a part of the memory core to be repaired Redundancy information loaded from the outside into the memory Time at which the repair is done
2229/70 2229/72 2229/723 2229/726 2229/74 2229/743	 correct operation, subsequent repair or testing stores during standby or offline operation Indexing scheme relating to G11C 29/70, for implementation aspects of redundancy repair Location of redundancy information Redundancy information stored in a part of the memory core to be repaired Redundancy information loaded from the outside into the memory Time at which the repair is done After packaging
2229/70 2229/72 2229/723 2229/726 2229/74 2229/743 2229/746	 correct operation, subsequent repair or testing stores during standby or offline operation Indexing scheme relating to G11C 29/70, for implementation aspects of redundancy repair Location of redundancy information Redundancy information stored in a part of the memory core to be repaired Redundancy information loaded from the outside into the memory Time at which the repair is done After packaging Before packaging